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Licenciado em Engenharia de Micro e Nanotecnologias

# Field-Effect Transistors Based on Zinc Oxide Nanoparticles

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# ABSTRACT

This work reports the development of field-effect transistors (FETs), whose channel is based on zinc oxide (ZnO) nanoparticles (NPs). Using screen-printing as the primary deposition technique, different inks were developed, where the semiconducting ink is based on a ZnO NPs dispersion in ethyl cellulose (EC). These inks were used to print electrolyte-gated transistors (EGTs) in a staggered-top gate structure on glass substrates, using a lithium-based polymeric electrolyte.

In another approach, FETs with a staggered-bottom gate structure on paper were developed using a sol-gel method to functionalize the paper's surface with ZnO NPs, using zinc acetate dihydrate  $(ZnC_4H_6O_4\cdot 2H_2O)$  and sodium hydroxide (NaOH) as precursors. In this case, the paper itself was used as dielectric.

The various layers of the two devices were characterized using X-ray diffraction (XRD), scanning electron microscopy (SEM), Fourier Transform Infrared spectroscopy (FTIR), thermogravimetric and differential scanning calorimetric analyses (TG-DSC). Electrochemical impedance spectroscopy (EIS) was used in order to evaluate the electric double-layer (EDL) formation, in the case of the EGTs.

The ZnO NPs EGTs present electrical modulation for annealing temperatures equal or superior to 300 °C and in terms of electrical properties they showed On/Off ratios in the order of 10<sup>3</sup>, saturation mobilities ( $\mu_{Sat}$ ) of 1.49x10<sup>-1</sup> cm<sup>2</sup>(Vs)<sup>-1</sup> and transconductance (g<sub>m</sub>) of 10<sup>-5</sup> S.

On the other hand, the ZnO NPs FETs on paper exhibited On/Off ratios in the order of  $10^2$ ,  $\mu_{Sat}$  of  $4.83 \times 10^{-3}$  cm<sup>2</sup>(Vs)<sup>-1</sup>and g<sub>m</sub> around  $10^{-8}$  S.

**Keywords:** Zinc oxide, ethyl cellulose, electrolyte-gated transistor, printed electronics, screen-printing, sol-gel, paper electronics.

#### RESUMO

Este trabalho reporta o desenvolvimento de transístores de efeito de campo (FETs), cujo canal é constituído por nanoparticulas (NPs) de óxido de zinco (ZnO). Assim, mediante o uso da técnica de impressão *screen-printing*, foram usadas e desenvolvidas tintas, uma das quais a semicondutora que consiste numa dispersão de NPs de ZnO em etilcelulose (EC). Assim imprimiram-se, num substrato de vidro, *electrolyte-gated transistors* (EGTs) numa estrutura *staggered-top gate* usando um eletrólito polimérico à base de lítio.

Numa outra abordagem, num substrato de papel foram desenvolvidos FETs numa estrutura *staggered-bottom gate*, recorrendo-se ao método sol-gel para funcionalizar a sua superfície, com NPs de ZnO, através de dois percursores acetato de zinco dihidratado (ZnC<sub>4</sub>H<sub>6</sub>O<sub>4</sub>·2H<sub>2</sub>O) e hidróxido de sódio (NaOH). Para estes dispositivos o papel foi usado como dielétrico.

As diferentes camadas que compõem os dois tipos de dispositivos foram caracterizadas por difração de raio-x (XRD), microscopia eletrónica de varrimento (SEM), espectroscopia no infravermelho por transformada de Fourier (FTIR), análise termogravimétrica e calorimetria diferencial de varrimento (TG-DSC). A espectroscopia de impedância eletroquímica (EIS) foi usada para avaliar a formação das *electric double-layers* (EDLs) no caso dos EGTs.

Os ZnO NPs EGTs apresentaram modulação elétrica para temperaturas de recozimento iguais e superiores a 300 °C e em termos de propriedades elétricas apresentaram razões On/Off na casa dos  $10^3$ , mobilidade de saturação ( $\mu$ sat) de  $1.49 \times 10^{-1}$  cm<sup>2</sup>(Vs)<sup>-1</sup> e transcondutância (gm) de  $10^{-5}$  S.

Por outro lado, os FETs desenvolvidos no papel apresentaram uma razão On/Off que ronda os  $10^2$ , uma  $\mu_{Sat}$  de  $4.83 \times 10^{-3}$  cm<sup>2</sup>(Vs)<sup>-1</sup>e g<sub>m</sub>  $10^{-8}$  S.

**Palavras-chave:** Óxido de zinco, etilcelulose, *electrolyte-gated transistor*, eletrónica impressa, *screen-printing*, sol-gel, eletrónica em papel.

# LIST OF ABBREVIATIONS

- a.u. Arbitrary units
- AC Alternating current
- AFM Atomic force microscopy

ATR-FTIR – Attenuated total reflectance - Fourier transform infrared spectroscopy

CE – Counter electrode

CEMOP – Centro de Excelência de Optoelectrónica e Microeletrónica de Processos

CENIMAT|i3N – Centro de Investigação de Materiais|Instituto de Nanoestruturas, Nanomodelação e Nanofabricação

- CPE - Constant phase element CSPE - Composite solid polymer electrolyte CV - Cyclic voltammetry DI Deionized DSC - Differential scanning calorimetry EC - Ethyl cellulose ECM - Equivalent circuit model - Electrochemical transistor ECT EDL - Electric double-layer EDLT – Electric double-layer transistor EGT - Electrolyte-gated transistor - Electrochemical impedance spectroscopy EIS EtOH – Ethanol FET - Field-effect transistor FNG - Flexible nanogenerator FSR - Felix Schoeller raw FWHM - Full width at half-maximum GZO – Gallium zinc oxide ICDD – International centre for diffraction data IPA - Isopropanol ITO - Indium Tin Oxide MIF - Metal ion free MOSFET - Metal-oxide-semiconductor field-effect transistor MW - Molecular weight - Nanoparticles NPs NRs - Nanorods OFETs - Organic field-effect transistors OLEDs - Organic light emitting devices PE - Printed electronics PET - Polyethylene terephthalate PVD - Physical vapour deposition RE - Reference electrode RT - Room temperature
- S/D Source and drain
- SEM Scanning electron microscope
- STA Simultaneous thermal analyzer
- TFT Thin film transistor
- TG Thermogravimetry
- UV Ultra-violet
- WE Working electrode
- XRD X-ray diffraction

# LIST OF SYMBOLS

$ au_f$	– Fall time
$ au_r$	– Rise time
μfe	<ul> <li>Field-effect mobility</li> </ul>
µ <sub>Sat</sub>	<ul> <li>Saturation mobility</li> </ul>
Cb	<ul> <li>Electrolyte bulk capacitance</li> </ul>
CDL	<ul> <li>Capacitance of electric double-layer</li> </ul>
Ceff	<ul> <li>Effective capacitance</li> </ul>
Ci	<ul> <li>Capacitance of the dielectric layer</li> </ul>
<b>g</b> m	<ul> <li>Transconductance</li> </ul>
IDS	– Drain current
l <sub>GS</sub>	<ul> <li>Gate leakage current</li> </ul>
Im (Z)	<ul> <li>Imaginary part of impedance</li> </ul>
loff	<ul> <li>Off state current</li> </ul>
lon	<ul> <li>On state current</li> </ul>
L	<ul> <li>Channel length</li> </ul>
Rb	<ul> <li>Electrolyte bulk resistance</li> </ul>
Re(Z)	<ul> <li>Real part of impedance</li> </ul>
Rext	<ul> <li>Exterior contact resistance</li> </ul>
rms	<ul> <li>Root mean square</li> </ul>
S₅	<ul> <li>Subthreshold swing</li> </ul>
V <sub>DS</sub>	<ul> <li>Voltage between drain and source</li> </ul>
Vgs	<ul> <li>Voltage between gate and source</li> </ul>
Von	<ul> <li>Turn-on voltage</li> </ul>
VTh	<ul> <li>Threshold voltage</li> </ul>
W	<ul> <li>Channel width</li> </ul>
Y <sub>0</sub>	- Capacitance of a constant phase element
Z	– Impedance
α	<ul> <li>Fractal surface character</li> </ul>
ρ	<ul> <li>Bulk resistivity</li> </ul>
σ	<ul> <li>Electrical conductivity</li> </ul>

 $\sigma_i$  – Ionic conductivity

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#### Motivation

Nowadays, printed electronics (PE) has become a hot-topic since there is a strong interest in replacing conventional silicon-based technology by simpler processing techniques in some low cost consumer electronics. Comparing the two technologies (conventional and PE) there are some clear advantages for the latter one, which are related to factors such as reduced fabrication costs associated to the manufacturing processes, the wasted material and benefits of the individual printing techniques (flexo, screen, rotary-screen, inkjet and off-set printing).[1] Out of these advantages other opportunities arise, such as the use of flexible substrates (e.g. polyethylene terephthalate (PET) or even paper) in order to design ultra-cost-effective, flexible, thin and environmentally friendly electronic devices. Additionally, they enable the production of large area printing on flexible substrates by roll-to-roll (R2R) processes, surpassing, in terms of throughput, the standard silicon wafer technologies available. Apart from that, printing techniques will reduce significantly the complexity of the manufacturing process, when lithography and etching steps are no longer necessary for circuit production.[2] Regarding the market needs, the IDTechEx Research predicts that for conductive inks and pastes a gross market revenue of \$2.8 bn and \$3 bn will be reached in 2020 and subsequently in 2025, respectively.[3]

Within this broad topic, the focus of this work is on the development of key electronic devices with low-cost materials (i.e. ink preparation for printing) at a laboratory scale, which could be compatible at an industrial scale in a R2R process. In this case, the emphasis will be on the semiconductor layer for field-effect transistors (FETs), in particular, the formulation of inks based on zinc oxide (ZnO) nanoparticles (NPs) dispersed into a cellulose matrix based on ethyl cellulose (EC), which will work as a thickening agent. Furthermore, oxide semiconductors have already shown outstanding performances in electronic applications.[4] Nevertheless, and regarding PE, organic semiconductors have been preferred since they can be easily processed into inks, particularly the polymers. Nonetheless, inorganic semiconductors can also be solution-processed but, in comparison to organic alternatives, high temperatures are fundamental, in order to remove binders or stabilizers. These so-called burn-out temperatures could compromise their application on flexible substrates.[5] Nevertheless, some communications have been made concerning inorganic semiconductors on electrolyte-gated transistors (EGTs) and many efforts have been made with the purpose to lower the working temperatures.[6][7]

Accordingly, it will be possible to build fully printed EGTs, using only screen-printing. These types of devices, apart from being printable, can operate at low voltages, owing to the high capacitance provided by the electrolyte's electric double-layer capacitance ( $C_{DL}$ ), which works as the dielectric layer.[8] However, due to the burn-out temperatures that are needed to degrade the binder, the intended EGTs will be built on glass substrates.

At the same time, paper electronics, has been undergoing a remarkable progress. Some of the most important benefits of paper are related to its low-cost and fast fabrication as well as its disposable and eco-friendly character.[9] Moreover, the potential of paper has been widely demonstrated in various applications such as a substrate for devices, sensors, solar cells, gas sensors and transistors, as well as an active part, more specifically as the dielectric layer in FETs, memories, and CMOS.[9]–[15]

Concerning the work that has been developed and is still ongoing by CENIMAT|i3N with this remarkable material, the possibility to functionalize cellulose fibers with oxide semiconductors, namely ZnO, through a sol-gel method, at room temperature, will be under study. As a result FETs, where paper is substrate, dielectric and at the same time acting as the semiconductor, are expected.

# **Objectives**

The main purpose of this dissertation is to design, fabricate and characterize field-effect transistors (FETs) combining cellulose with Zinc Oxide (ZnO) nanoparticles (NPs). The focus will be on the development of printed electrolyte-gated transistors (EGTs) where the ZnO NPs will be used as the semiconductor material in a staggered top-gate architecture, with interdigital indium tin oxide (ITO) or conductive carbon as source and drain contacts and silver as gate electrodes.

In parallel, the possibility to coat conventional paper with ZnO nanoparticles by sol-gel method in aqueous medium of zinc acetate dihydrate ( $ZnC_4H_6O_4 \cdot 2H_2O$ ) and sodium hydroxide (NaOH) will also be demonstrated. Consequently, it shall be possible to build a FET, where paper can be used not only as a substrate, but also as the dielectric and the semiconductor, after functionalizing the cellulose fibers on one side of the paper with ZnO NPs. Here a staggered bottom-gate architecture will be adopted, where source, drain and gate electrodes will be deposited by physical vapour deposition (PVD) techniques.

Therefore, for a better understanding, the main following objectives will be covered:

- Characterization of the properties of ZnO nanoparticle films deposited by screen printing technique and sol-gel method;
- Study of the influence of temperature on the degradation of EC, working as a sacrificial binder of ZnO screen-printed films.
- Study of Electrochemical Impedance Spectroscopy (EIS) of the lithium based polymer electrolyte and paper, for ZnO NPs EGTs and paper ZnO NPs FETs respectively;
- EIS characterization of the ZnO screen-printed films;
- Electrical characterization of the interdigital contact electrode materials for EGTs;

Then, the electrical characterization of the final devices, EGTs and FETs, will be performed in order to understand their performance.

## 1. INTRODUCTION

Recent developments over the last decade on the field of nanostructured zinc oxide (ZnO) surfaces and nanoparticles (NPs) opened the way for application in several areas, ranging from thin-film transistors (TFT)[16]–[18], dye-sensitized solar cells[19], piezoelectric devices[20], gas sensors [21], opto- and microelectronics[22] to biomedical applications, such as antibacterial and antifungal agents in medicine[23]. Figure 1.1 exemplifies the implementation of ZnO nanostructures in some of such devices.



Figure 1.1 – Three applications of ZnO nanostructures a) as an UV photodetector[24], b) as an anti-bacterial agent[25] and c) as a flexible nanogenerator (FNG).[26]

The inherent electrical properties of ZnO make it a well-established candidate for its subsequent integration into semiconducting devices, such as transistors. The following sections will give a brief introduction to ZnO nanostructures, as well to transistor technologies and the concept used in this work of electrolyte-gated transistors (EGTs) and its advantages, especially in the context of printed electronics (PE).

#### 1.1. Zinc oxide: Main features, structures and its application in electronics

Over the last decades, interest in the synthesis and application of nanoscale materials has been growing, due to their unique mechanical, electrical, optical and chemical properties that are different from the bulk, particularly, due to high surface-to-volume ratio and spatial confinement. This brings new approaches in the field of electronic devices. In this specific area the transistor (characterized as an electric On-Off switch) is one of the most crucial semiconducting electronic components in nowadays technologies.[27] The focus for these devices is on the improvement of their performance, which is closely relate to the semiconductor capability of free charge carrier accumulation in the transistor channel at the semiconductor/dielectric interface.[28]

In this context, ZnO is characterized as an excellent inorganic n-type semiconductor material, which has a direct bandgap of 3.37 eV and a free-exciton binding energy of 60 meV at room temperature, where the most common crystalline phase is of hexagonal wurtzite nature.[16] Various methods of synthesis, such as chemical vapour deposition (CVD)[29], hydrothermal methods[24][19] or via sol-gel method[30] have been reported in the way to tailor a wide range of ZnO nanostructures, such as nanoparticles, nanorods, nanowires or thin films. Different shapes, sizes and morphologies determine the chemical and physical properties of the ZnO, as well as the corresponding electrical, optical and piezoelectric ones.[24] Also its long durability, heat resistance (melting point 1975 °C) are preceded over organic semiconductor alternatives.[28]

Table 1.1 summarizes some of the most important publications that have been made regarding the use of inorganic semiconductors on EGTs, where high mobilities stand out. Additionally improved stability and performance are always by far superior to organic alternatives, which are nonetheless suitable owing to their low-cost processing (without vacuum) and high flexibility.[6] Still, organic semiconductors present issues regarding their stability in ambient conditions, as it is the case of oxygen doping in air promoting large off-currents in organic field-effect transistors (OFETs).[31] As depicted in

the same table, different techniques such as printing have been employed for EGTs fabrication, but to our knowledge, always at least one of the layers has not been printed. Consequently, the main goal of this work is to achieve fully-printed inorganic EGTs.

Semiconductor	Deposition technique	Post- treatment	Electrolyte	V <sub>DS</sub> (V)	V <sub>Th</sub> (V)	On/Off	μ (cm²(Vs) <sup>-1</sup> )
ZnO [32]	Spin-coating	280 °C	Ion Gel	0.7	1.16	2.64x10⁵	12.1
In <sub>2</sub> O <sub>3</sub> [33]	Inkjet	-	PVA+KF	0.4	0.54	2x10 <sup>3</sup>	0.8-0.26
ITO [5]	Inkjet	400 °C	CSPE	0.8	- 0.22	2 x 10 <sup>4</sup>	5
ZnO [34]	Aerosol Jet Printing	250°C	Ion Gel	0.1	0.97	2.15x10⁵	1.67
GIZO [7]	Spin-coating	250 °C	CSPE	1	1.9	1x10 <sup>5</sup>	1
IGZO [35]	Spin-coating	350 °C	KCI	0.5	0.16	1.4x10 <sup>7</sup>	10.82

**Table 1.1** – Key parameters of the reported EGTs, where inorganic semiconductores were implemented, i.e. the deposition technique, the temperature of the post-treatment, the used electrolyte, the voltage between drain and source ( $V_{DS}$ ), the threshold voltage ( $V_{Th}$ ), the On/Off ratio and the mobility ( $\mu$ ).

Since ZnO can be processed and printed, using solution precursors, ZnO obtained from sol-gel method[30] and commercial ZnO nanoparticles (NPs) will be explored in ways to work as the semiconductor layer in FETs and EGTs, respectively. In the next subsection, the mode of operation of these two types of devices will be briefly explained.

#### 1.2. Transistor technologies and electrolyte-gated transistors

Since the development of the first transistor by John Bardeen and Walter Brattain, the information technology has been revolutionized.[36] Particularly, FET has become one of the most implemented semiconductor devices. The fundamental characteristic of these devices is the modulation of a current between two electrodes (source and drain, I<sub>DS</sub>) with a voltage applied at a third electrode (gate, V<sub>GS</sub>). The term field-effect derives from the fact that an electric field, generated by the application of V<sub>GS</sub>, develops throughout the channel region, capable of inducing (accumulating) charge carriers in the channel, which can be collected by the drain electrode (in the case of an n-type FET). The field-effect mode has been harvested for many microelectronic applications and culminated in cutting edge technologies like the metal-oxide-semiconductor field-effect transistor (MOSFET)[37] or the thin-film transistor (TFT).[38] Whereas MOSFETs rely on diffusion/implantation processes into crystalline silicon substrates (wafers) [27] TFTs are fabricated using layer-by-layer deposition techniques. The interest into TFTs was governed mostly by the need for higher substrate varieties and fabrication in large areas, resulting in modern application fields such as displays, paper and flexible electronics.[4][10][11]

The use of electrolytes instead of a conventional dielectric layer in a FET results in an EGT. One of the key features aimed for an electrolyte is the low electrical but high ionic conductivity ( $\sigma$  and  $\sigma_i$ , respectively). This allows the electrolyte to behave as a pseudo dielectric, bridging the gap between a conductive gate electrode and the channel region. By applying a V<sub>GS</sub> ions migrate in the electrolyte, in this case in the composite solid polymer electrolyte (CSPE), accumulating at the respective interfaces, forming electric double-layers (EDLs) as illustrated in Figure 1.2 a). The electric field at these EDLs becomes very high and is capable of effectively inducing charges into the semiconductor.[39] This effect can be used for transistor applications,[8] to investigate insulator-to-metal transitions[40] or superconductivity behaviour of insulators.[41]

The evolution from conventional dielectric materials (oxides and nitrates) to electrolytes was governed by the need for higher transistor driving currents, since it is directly proportional to the capacitance of the dielectric layer per unit area ( $C_i$ ), as we can see in equation 1.1:

$$I_D = \frac{W\mu_{FE}C_i}{L} \left[ (V_G - V_T)V_D - \frac{V_D^2}{2} \right]$$
(Eq. 1.1)

where W and L are the channel width and length, respectively, and  $\mu_{FE}$  the field effect mobility. Electrolytes are capable of reaching values in the order of 1 – 10  $\mu$ Fcm<sup>-2</sup>, outperforming even high-k dielectrics[42]–[44], consequently their integration into semiconductor devices became straightforward. EGT applications range from textile fibers, biosensors, supercapacitors or electrochromic displays.[8] High capacitance dielectrics also enable the EGTs to operate at reduced voltages, advantageous for low power dissipation devices.[34] Furthermore, the inherent properties of electrolytes as gates offer not only exceptionally low source and drain contact resistances,[45] still presenting a downside in conventional transistors, but also new possibilities in PE devices, owing to the solution processability of many solid electrolytes.[46]–[48]

A considerable drawback to employ EGTs remains in their significant gate leakage currents (I<sub>GS</sub>), arising from considerable charging currents of the ion accumulation process.[8] Consequently, the decision to employ EGTs will depend on understanding which figure of merit is most crucial for a given application.[49] As well, the ionic conductivity of the electrolyte is crucial for the intended application since the ionic charge motion, in the electrolyte, depends on the diffusion and the migration, owing to the concentration gradient and the electric field, respectively. The nature of the electrolyte either liquid, solid or gel, is also significant for the ion motion process.[39] As a result, the time response of the EGTs will depend the ionic conductivity and the interaction with the semiconductor layer.[50]

For this work, EGTs as depicted in Figure 1.2 b) were the most suitable solution as the aim was the fabrication and characterization of fully printed FETs.



**Figure 1.2** – **a)** Cross-section schematic representation of the staggered top-gate structure with interdigital source and drain contacts adopted for the fully printed ZnO NPs EGTs on glass substrate. The respective EDL formations at each interface is also illustrated. **b)** A 3D schematic representation, where bottom black and top silver layers are the source/drain and gate electrodes, respectively. Whereas the white and the yellow layers represent the ZnO NPs and the composite solid polymer electrolyte (CSPE) film, respectively.

Since printing was selected as the deposition technique for device fabrication in this work, the next section will introduce some fundamentals about PE and highlight advantages and disadvantages of the processes involved.

#### 1.3. Printed electronics and printing techniques

Printing processes have developed/adapted with the progress in electronic manufacturing technology and it is prominent that a large potential can be provided, by combining this technology with the notorious advances in nanomaterials for electronic applications. These continuous demands for new materials, new methods or techniques, make PE, the key technology for designing ultra-cost-effective, as well as flexible, thin, low power consuming, and environmentally friendly electronic devices. Some of them are already known as large area printed pressure sensors[51]–[53], organic light emitting devices (OLED)[54]–[56] or solar cells.[57]

Screen-, flexo-, gravure-, offset- and inkjet printing[2] are the main printing methods that have been reported in a wide range of electronic applications; not only for coatings but also to develop micro-structures and accurately define patterning forms. The selection of the method, which suits best the

intended application, depends on a number of properties, including the required printing quality, the substrates, the inks and especially the resolution.

Printing techniques offer a variability of benefits against photolithography and vacuum processes since they are fast, low-cost, offer fast prototyping, allow the reduction in material waste and they enable the production of large area printing on flexible substrates by roll-to-roll (R2R) processes. [58][59] Nevertheless, the resolution limits of the current printing techniques have an effect on the performance of printed devices. In addition, as all printable materials are in solution form, their physical and chemical stability, as well as viscosity, compatibility of the solvents and surface energies are the major paradigms in choosing the suitable printing technique and evidently in the devices final performance.[54][56]–[58]

It is desired to fabricate fully functional devices, using solely one printing technique instead of a combination of the ones mentioned above, as this facilitates the fabrication process, leading to a more cost-effective production. This approach was shown in recent scientific publications in a wide range of applications: as patterning source and drain electrodes[62], or for all-printing stretchable electrochemical devices.[63]

Therefore, in this thesis, screen-printing was chosen as the only fabrication technique to produce the EGTs. Owing to the printed circuit board industry, it is the most versatile printing technique and a quite mature technology for PE, in comparison to the ones mentioned before.[2] High aspect ratio of printed objects is the most distinct feature of this technique. In addition, a wide range of thicknesses, reaching from a few  $\mu$ m up to 100  $\mu$ m can be achieved, which cannot be obtained by other printing techniques.[64]

This technique is based on a screen mesh, which may be polyester or stainless steel, with a defined printing pattern. This pattern is defined by photolithography of a light sensitive emulsion on the mesh. A squeegee, of rubber or metal, moving over the screen, provides shear stress to the ink (or printable paste), consequently decreasing its viscosity (viscoelasticity) and allowing it to cross through the open areas onto the substrate. Solution viscosity, printing speed, angle and geometry of the squeegee, mesh size, material, strength and snap-off (distance between screen and substrate) are the main factors to consider in order to achieve high-resolution patterning (30 - 50 µm), through this printing technique.[64] Viscosities, typically between 500 - 5000 cPs are referred to as desirable for this technique, since inks with low viscosity will run through the mesh rather than dispensing out of it.[64] As well, to obtain a high-resolution line width a compromise between surface energies, either of the substrate or the ink, is required. Low surface energies of the substrate provides reduction of the wettability of the printable paste, which leads to improved line resolutions. Moreover, as we can change the wettability of the substrate, by controlling its surface energy, low viscosity inks can also be used to achieve good resolutions.[60] A schematic drawing of the used screen-printing system, present in CENIMAT|i3N, is displayed in Figure 1.3.



Figure 1.3 – Schematic representation of the custom-made screen-printing present in CENIMAT|i3N laboratorys. Adapted from[65].

Considering the required ink properties and their influence on the used printing technique the next subsection will give a short overview of the ink preparation as well as some crucial remarks on its composition.

#### 1.3.1. Ink formulation and properties for thick films

The synthesis of a nanoparticle thick-film (thicknesses in micro scale) ink must be made by a careful selection of the raw materials, so that its characteristics do not compromise the intended application. The ink must be prepared dispersing the desired inorganic powders/precursors in a viscous liquid, the vehicle, which is responsible for the deposition of the powder onto the substrate. Both of these components must be dispersed along with an organic or sacrificial binder with a solvent and a wetting agent. For this, resin or polymeric binders such as cellulosic polymers, as is the case of ethyl cellulose (EC) is widely used for industrial screen-printing as it provides good printing and levelling.[66] The sacrificial binder is used in order to hold the inorganic powders together and give the ink the intended rheological properties.[67] Additionally, solvents with low vapour pressure at room temperature and a high vapour pressure at 100 - 150 °C, should be selected, in order to prevent ink drying by evaporation on the screen and enable rapid drying of the printed parts by annealing.

Thereby, to obtain the mechanical and electrical required properties, which are given by the powder, the vehicle must be eliminated ("burned-out"), so there will be no trace of it in the final film. Nevertheless, the properties of the thick-film are not just influenced by the bulk properties of the inorganic powders, but also by their surface area, particle size, tap density, purity and interface quality. For instance, surface area influence viscosity, particle size and their dispersion effect, which in turn has an effect on ink behaviour, film surface smoothness, film conductivity, film density, printing and its adhesion to the substrate.[68] Due to the presence of agglomerates, large interface roughness between the transistor channel and the gate insulator can occur, forming charge traps, which makes the charge transfer between source and drain electrodes difficult. Consequently, the turn-on voltage (Von) and the subthreshold swing (S<sub>s</sub>) of the devices can be impaired. One way of overcoming this problem is to stabilize the nanodispersions with surfactants.[5] However, the presence of the vehicle, as well as surfactants or additives decline the electrical performance of the thick-film, likewise the type of substrate that can be used, since high temperatures or UV irradiation is needed to burn them out.[5][65]

#### 1.4. Inorganic field-effect transistors on paper

Paper electronics appears as a new area of technology, which has begun to show that it is possible to counteract all the issues related to a decrease in waste material, making technology cheaper, disposable and eco-friendly, even if this new approach is on an early stage of development. Furthermore, paper is also recyclable, lightweight and widely used as a flexible substrate in everyday life. Additionally and most importantly manufacturing process can exceed 100 kmh<sup>-1</sup>, making it cheap ( $\approx$  0.1 cent dm<sup>-2</sup>) compared to other substrates used in electronics, like for instance polyethylene terephthalate (PET  $\approx$  2 cent dm<sup>-2</sup>).[9]

The first step in the application of paper as a substrate in electronics, was given in 1968[31], having today several applications of it as substrate for sensors, solar cells, gas sensors or displays. Nonetheless, many efforts have been made to make it more functional beyond a simple substrate.[69] Fortunato *et al.* have shown for the first time (see Figure 1.4 a)), using this remarkable material, that in addition to the substrate, it can also work as an active part i.e. dielectric in FETs.[11] The benefit of being applied as dielectric is related to its foam-like structure that enables moisture retention, which produces a large gate capacitance at low frequencies due to the free charges.[70]

This technological leap made their application in memory transistors[14] and CMOS devices[15] possible. Recent studies also confirm that the properties of the paper-based transistors are affected by the structure, fiber type and thickness of the paper.[12][13]

Taking these approaches into account another possibility will be explored using, once again, ZnO NPs as the functional semiconducting layer. However, instead of using physical vapour deposition (PVD) techniques, the sol-gel method proposed by Jaber and Laânab[30] will be used. Consequently,

it will be possible to coat the cellulose fibers of the paper substrate with ZnO nanoparticles under ambient atmosphere at room temperature. Thus, to build an interstate structure (similar to the one in Figure 1.4 b)), where this time paper can play three different roles: substrate, dielectric and semiconductor after being functionalized, is feasible.



Figure 1.4 – a) An image of the developed FETs in CENIMAT|i3N where paper was applied as substrate and dielectric and b) its schematic representation. Adapted from [13].

# 2. MATERIALS AND METHODS: FABRICATION, OPTIMIZATION AND CHARACTERIZATION PROCESS OF EGTs and FETs

This chapter aims to present all the steps that were taken for the production and characterization of EGTs on glass and FETs on paper. First, the formulation of the semiconductor layer will be presented, which in case of EGTs is a printable paste, containing a dispersion of ZnO nanoparticles in a sacrificial binder EC. In case of the paper ZnO NPs FETs, paper was coated with ZnO NPs by sol-gel method, in an aqueous solution of zinc acetate dihydrate and sodium hydroxide.

Secondly, the architecture chosen for each transistor type will be displayed as well as the steps and techniques that were used for all the layer depositions.

Finally, all the characterization techniques selected to study the morphology, structure and stability of the semiconductor and electrolyte layers will be listed. In the end it will be shown how the electrical characterization of the final devices was conducted.

#### 2.1. ZnO NPs ink formulation materials and reagents

The methods used for preparing ZnO NPs screen-printing paste were based and adapted from the literature.[71] First, the vehicle was prepared by dissolving 5 %wt Ethyl Cellulose 300 cP ( $C_6H_7O_2$  ( $OC_2H_5$ )<sub>3</sub>; CAS: 9004-57-3) from Aldrich on an 80:20 toluene/ethanol solution ( $C_6H_5CH_3$ ; CAS: 108-88-3/  $C_2H_6O$ ; CAS: 64-17-5). After complete dissolution, which takes around 12 hours under stirring at 600 rpm, 0.25, 0.5, 0.75 and 1 g of ZnO nanopowder, <100 nm particle size (CAS: 1314-13-2) from Aldrich were added always in the same amount of vehicle. The solutions should be kept under continuous stirring until their complete dispersion.

#### 2.2. ZnO semiconductor layer by sol-gel method

As mentioned in section 1.4 and taking into account the work done by Jaber and Laânab[30] a piece of Felix Schoeller raw (FSR) paper, was submersed in an aqueous solution. For that, 4 cm<sup>2</sup> of FSR, which consist of pressed cellulose fibers with high porosity and 141  $\mu$ m of thickness, obtained from Felix Schoeller with, was covered on one side by adhesive kapton tape. The solution was prepared by mixing 1.757 g of zinc acetate dihydrate (CAS : 5970-45-6, ZnC<sub>4</sub>H<sub>6</sub>O<sub>4</sub>·2H<sub>2</sub>O, MW: 219.51) from Sigma-Aldrich and 0.796 g sodium hydroxide (NaOH), previously dissolved in 100 ml and 20 ml of deionized water, respectively. Firstly, the paper must be immersed in the zinc acetate solution and then NaOH at a rate of 2 ml/min was added. While adding NaOH, the stirring should increase to 1300 rpm and be maintained for 1h. Finally, the paper was washed with deionized water to remove excess and left drying in air. It is necessary to supervise the process because the paper can glue up the edges of the beaker and can get stuck due to the stirrer.

#### 2.3. Fabrication and optimization of the ZnO NPs EGTs and paper ZnO NPs FETs

#### 2.3.1. ZnO NPs EGTs by screen-printing

In case of ZnO NPs EGTs, a staggered top-gate architecture was adopted. Since ZnO NPs are intended to be used as semiconductor layer, two considerations were made relatively to source and drain (S/D) electrodes. First, ITO interdigital S/D electrodes were pattern via photolithography, as illustrated in Figure 2.1, and carbon interdigital S/D electrodes by screen-printing as illustrated in Figure 2.2. Also, in this last figure is briefly described all the printing steps that were taken for achieved the fully-printed devices. Nevertheless, in Annex A, a more detailed description of the all steps for the EGTs development can be found.



Figure 2.1 - Schematic representation of the ITO interdigital S/D electrodes patterned via photolithography.



Figure 2.2 – Schematic representation of the developed fully-printed ZnO NPs EGTs.

#### 2.3.2. Paper ZnO NPs FETs

As mentioned in 2.2 the first step consisted in growing ZnO nanoparticles on the cellulose fibers on the surface of FSR paper, which was itself used as a dielectric for the intended devices. Figure 2.3 displays a simple schematic representation, of the steps that were taken in order to achieve a staggered bottom-gate architecture, for the paper ZnO NPs FETs. Nevertheless, in Annex A a more detailed description of the whole fabrication is shown.



Figure 2.3 - Schematic representation of the developed paper ZnO NPs FETs.

#### 2.4. Characterization techniques

Several techniques were used in order to characterize the various layers of the transistors. The rheological behaviour of the ZnO ink and the lithium-based polymer electrolyte was evaluated using Bohlin Gemini HR<sup>NANO</sup> rotational rheometer, with parallel plates geometry (20 mm diameter and 500  $\mu$ m gap) for steady-state measurements. Temperature was kept at 25 °C and, before starting the measurements, samples were subjected to a pre-shearing stage, with a pre-shear of 1 s<sup>-1</sup> applied for

30 s, followed by an equilibration time of 180 s. A solvent trap was used in order to avoid evaporation. The steady-state measurements were performed for shear rates up to 1000 s<sup>-1</sup>.

Atomic force microscopy (AFM) was performed in non-contact mode using an Asylum MFP-3D instrument. The resolution of the image was 512 lines by 512 columns and the scan size was 5×5  $\mu$ m<sup>2</sup> and 20×20  $\mu$ m<sup>2</sup>.

Both semiconductor layers were characterized by SEM-FIB using a Carl Zeiss AURIGA CrossBeam workstation instrument. As well as the crystallinity and structure of the samples were obtained by X-Ray Diffraction (XRD, PANalytical, model X'Pert Pro), in Bragg-Brentano geometry with Cu K $\alpha$  line radiation ( $\lambda$ =1.5406 Å) at 45 KV and 40 mA. Particularly, in the case of ZnO screen-printed films XRD analysis was performed first at 30 °C and subsequently between 100 °C and 500 °C, with a step of 50 °C.

Fourier transform Infrared (FTIR) spectroscopy was applied in order to evaluate the EC, toluene and ethanol thermal degradation. The ZnO ink was screen-printed on glass substrates, previously cleaned in acetone, IPA and DI water and then exposed to different annealing temperatures, ranging from 100 °C to 450 °C, with a step of 50 °C, on a hotplate. The spectra were acquired between 4500-500 cm<sup>-1</sup> by a Nicolet 6700 FTIR Thermo Electron Corporation device. In addition, with the same purpose of understanding the thermal degradation of the ink constituents, thermogravimetric and differential scanning calorimetry (TG-DSC) measurements were carried out on the semiconductor ink solution with a Simultaneous Thermal Analyzer (TG-DSC - STA 449 F3 Jupiter). Approximately 20 mg of each sample was loaded into an open Al crucible and heated from room temperature to 550 °C with a heating rate of 5 °Cmin<sup>-1</sup>, in ambient conditions.

Electrochemical Impedance Spectroscopy (EIS) was done using Gamry Instruments Reference 600 Potentiostat in order to determine:

- The capacitance-frequency dependency of the lithium-based polymer electrolyte samples inserted between stainless steel discs with an area of 1.039 cm<sup>2</sup> (see Figure 3.8 a)). The results were acquired in a frequency range of 1 MHz to 100 mHz with 25 mV as ac excitation voltage at 1 V dc.
- The capacitance-frequency dependency of FSR paper, using gold discs with an area of 1.77 cm<sup>2</sup> and in a frequency range of 1 MHz to 10 mHz with 5 mV as ac excitation voltage. Previously, both sides of the paper were coated with about 120 nm of aluminium by e-beam evaporation, in order to improve the electrical contact between the paper and the gold discs.
- The impedance spectroscopy of the ZnO thick films was evaluated in a frequency range of 1 MHz to 10 mHz with 25 mV as ac excitation voltage. For that, step number 2 and 3 of the Annex A were followed, but a wider range of temperatures was established, including room temperature, 100 °C and from 200 to 400 °C, with a step size of 50 °C.

The electrochemical response of lithium-based polymer electrolyte and the combination with annealed ZnO ink was evaluated by cyclic voltammetry (CV) through a Gamry Instruments Reference 600 Potentiostat. Doctor blade technique was used in order to deposit both layers, on stainless steel discs. In the case of the electrolyte, the layer was exposed, first to UV radiation during 5 min and, afterwards, dried on a hotplate at 70 °C. On the other hand, the ZnO thick-film was annealed, during 30 min at 350 °C. All films were electrochemically cycled from 4 to -4 V, at a scan rate of 10 mVs<sup>-1</sup>.

Furthermore, the Olympus BX51 microscope, and the software Cell A were used to measure the transistors' dimensions. In particular, the semiconductor channel lengths and widths were measured using a Leica IC80 HD microscope and the LAS V4.3 software.

Electrical measurements of the resistivity of carbon and silver electrodes were performed using the four-point probe technique (Jandel Enginneering Ltd) and the thickness of the screen-printed films were measured with an Ambios XP-Plus 200 Stylus profilometer.

The electrical characterization of both of the transistor types was performed in the dark at room temperature using an Agilent 4155C semiconductor parameter analyser connected to a Cascade Microtech M150 manual microprobe station, controlled by the software Metrics ICS.

## 3. RESULTS AND DISCUSSION

#### 3.1. Characterization and properties of ZnO NPs ink semiconducting layer

In this section, the focus will be on the development and characterization of both of the semiconductor and the electrolyte layers. As was already mentioned before, screen-printing depends highly on the used inks and their non-newtonian behaviour during the deposition process. Consequently, rheological measurements were performed on the used functional inks (ZnO and electrolyte).

After verifying a good dispersion of the powder and the viscous character of the solutions listed in section 2.1, thick films of ZnO NPs were printed on glass substrates, using a mesh model 77-55 (mesh count 190, aperture 81  $\mu$ m thread diameter 55  $\mu$ m).

After visual and microscope inspection, the solution with 1 g of ZnO powder resulted in best uniformity, compactness and adhesion, where films with an average thickness of 1.39  $\mu$ m were achieved. Therefore, this was the ink employed and characterized as the semiconducting layer.

After deposition, the vehicle's response to high temperature during the burn-out process will be investigated by TG-DSC, as this determines the necessary temperature at which the film should be subjected in order to retain solely its semiconductor content. The films will then go through a number of characterization steps to further investigate their structural and morphological properties (FTIR, SEM, and XRD) in respect to the applied annealing temperatures.

#### 3.1.1. Rheological measurements

The rheology of the ink is strongly dependent on the rheology of the vehicle since sacrificial binder and solvent are the main components for screen-printing inks. It is also pertinent to preserve good printability during the time it remains on the screen and the printing parameters must allow for high yield. Thus, the variation of the steady-state viscosity as a function of the shear rate was performed for ZnO NPs ink, vehicle and lithium-based polymer electrolyte, as shown in Figure 3.1.



Figure 3.1 – Viscosity as function of the sear rate for ZnO NPs Ink, vehicle (EC 5 wt% on toluene/ethanol) and lithium- based polymer electrolyte.

First, a decrease of the viscosity with increasing shear rate is noted, especially for vehicle and electrolyte, which is related with their viscoelastic properties, allowing them to cross through the screen open areas onto the substrate.

In the case of ZnO NPs ink it is possible to say the viscosity is practically independent of the shear rate applied. Furthermore, the addition of ZnO nanoparticles decreases the viscosity of the vehicle, particularly of the EC since it is a polymer working as a sacrificial binder. This fact is expected as a result of the presence of nanostructures inside a polymer nanocomposite (PNC), which can modify its structural, dynamical and viscous behaviour. These changes are arising not only from the high surface-area-to-volume ratio of the nanoparticles but also due to the strong polymer-nanoparticles

interactions, which affect the entanglement of the EC chains.[72] Also, It is possible to affirm that ZnO NPs ink shows a newtonian flow for the applied shear rate range, since there is no significant change in its viscosity during the measurement, except for 100 s<sup>-1</sup>, where only a slight change was verified. This indicates that the printed semiconducting films are less affected by printing parameters such as the applied force or velocity during the deposition. Consequently, reproduction of the films are favoured even when altering the deposition parameters, which happens when doing it by hand in a non-automated way. Nevertheless, it is necessary to take heed, since inks with low viscosities can pass through the mesh without the application of any shear stress. Furthermore, the formulated semiconducting ink shows good printability, good adhesion to the glass substrate and high uniformity which are crucial properties for instance for high interface quality and improved yield of the final EGT devices. Additionally, the ink was easily removed from the screen during the clean-up process with EtOH, which is desirable especially on an industrial scale with online R2R processes.

In contrast, the electrolyte exhibits mostly a non-newtonian behaviour. Furthermore, the fact that its dynamic viscosity is high becomes a problem when printed through the mesh, since the ink is blocked and it gets difficult to obtain a uniform printing pattern. This resulted in non-uniform films with defects, affecting the semiconductors coverage and consequently the performance of the devices. An illustration of the screen-printed electrolyte film on glass substrate can be accessed in Annex B. It might suggests that in order to achieve an improved printed layer a better control under the applied shear rate should be done. Through the homemade screen-printing it could be quite challenging; however, via an automatic one a better understanding of the phenomenon might be possible. As a result, snap-off, shear rate, angle, geometry and squeegee type could be investigated in the printed layers reproducibility.

#### 3.1.2. TG-DSC of the vehicle and ZnO NPs ink

Via Thermogravimetric-Differential Scanning Calorimetry (TG-DSC), it was possible to evaluate the thermal behaviour of the vehicle, specifically to quantify the range of temperatures needed to burn it out. The TG-DSC measurements were performed from room temperature to 550 °C; here however only temperatures at which important endothermic reactions were detected will be shown and discussed. The TG-DSC results of the vehicle are represented in Figure 3.2 a), where a maximum peak of 0.48 mWmg<sup>-1</sup> is observed for 93.9 °C. This peak is associated to an endothermic reaction, which represents the evaporation of the organic solvents. Simultaneously to this reaction, a significant mass loss is observed, further confirming the evaporation of the solvents i.e. toluene and ethanol, since their boiling points are 78 °C and 110.6 °C, respectively. In addition, for temperatures above 350 °C, there is almost no mass loss, which suggests that EC was fully degraded, which started to occur gradually above about 270 °C, as shown in Annex C.[73]



Figure 3.2 –TG-DSC curves of a) vehicle solution (EC 5 wt% on Toluene/ EtOH and b) ZnO NPs ink.

The TG-DSC data plot for ZnO NPs ink is shown in Figure 3.2 b). It is noticeable that the two graphs (Figure 3.2 a) and b) show a similar trend over the investigated temperature range, indicating almost no influence of ZnO NPs on the thermic behaviour of the vehicle. The degradation of the solvents is also perceptible due to the endothermic reaction at 103.2 °C, related with a high mass change and a 0.529 mWmg<sup>-1</sup> peak. Additionally, from both figures it is observable, that a mass loss starts to occur at

room temperature, which is associated to the low flash points of both solvents, 12 and 14 °C for ethanol and toluene, respectively. Once again, for temperatures above 270 °C degradation of EC, owing to the associated mass loss, is suggested. On the other hand, above 400 °C, there still is ZnO powder present in the crucible, since TG-DSC data still shows a linear positive mass value. This is not the case for the pure vehicle solution, reaching 0 % of initial mass for the final temperature. This observation indicates a 100 % thermal degradation of the vehicle; the desired effect of the burn-out process. Combining the knowledge of the individual measurements leads to the assumption that an annealing step above 300 °C of a screen-printed ZnO NPs thick film would lead to a pure ZnO NPs film, which can then be used as the functional semiconducting layer in an EGT.

The next subsection will focus on the burn out process but this time on ZnO NPs ink screenprinted on glass substrates. The idea is to verify through the Attenuated Total Reflectance-Fourier Transform Infrared Spectroscopy (ATR-FTIR), if thick films exhibit the same behaviour in relation to the increase in temperature, as in the previous subsection concerning their ink form.

#### 3.1.3. ATR-FTIR of the ZnO NPs ink

The study of the thermal decomposition of the vehicle, namely the EC content was studied also by ATR-FTIR. The semiconductor ink was screen-printed on glass substrates and annealed at different temperatures. In Annex DAnnex an ATR-FTIR spectrum of the compounds in solution form is also shown. Figure 3.3 shows the FTIR spectra for 24 °C, 300 °C and 450 °C. For EC, the peak at 3500 cm<sup>-1</sup> represents the stretching of O-H groups both in the closed ring structure and in intra/intermolecular hydrogen bonds. The peaks around 2980-2870 cm<sup>-1</sup> may indicate CH stretching and the distinct peak at 1375 cm<sup>-1</sup> refers to CH<sub>3</sub> bending. Additionally, the small peak at 1440 cm<sup>-1</sup> represents CH<sub>2</sub> bending, and the broad peak around 1100 cm<sup>-1</sup> may be due to C-O-C stretching in the cyclic ether.[74]



Figure 3.3 - ATR-FTIR spectra of the ZnO NPs ink after being screen-printed and annealeted at 24, 300 and 450 °C.

Annex E provides a better understanding of the temperature effect on the screen-printed films. At 100 °C, there are signs of thermal degradation of the ink, since there is a decrease of the absorbance peaks, however quite small. The spectra for 150 °C and 200 °C remain virtually the same, though, the spectrum for 250 °C shows a clear reduction of the absorbance peaks mentioned above, indicating the beginning of EC thermal decomposition. The absorbance peaks for EC have almost disappeared for 300 °C and finally, from 350 °C to 450 °C, there are no absorbance peaks corresponding to EC, meaning that the polymer has been degraded.

In addition to this, a notable loss of adhesion of the films to the substrates was identified after annealing, especially for those with annealing temperatures above 300 °C. This detail is expected since EC works as a binder (improves adhesion), which is lost after application of the burn-out temperatures

determined by TG-DSC and ATR-FTIR. Later, in subsection 3.7.2, the influence of these temperatures on the performance of the EGTs will be discussed.

#### 3.1.4. Structural and morphological analysis of ZnO NPs ink

SEM analysis was carried out with the purpose to explore the shape, morphology and size of the commercial ZnO NPs in the ink. Figure 3.4 a) shows the top surface of the printed thick film performed at room temperature. In spite of seeing some agglomerates and roughness, the printed film exhibits a good coverage of the glass substrate, resulting in good film uniformity.



**Figure 3.4** – **a)** The topographical view, obtained by SEM, of the top surface and XRD diffractogram, at 30, 300, 350 and 500 °C, of ZnO NPs Ink, **b)** SEM picture of the ZnO NPs dispersed in ink, and **c)** the corresponding 3D view of the top surface, with an area of 25  $\mu$ m<sup>2</sup> acquired by AFM.

X-Ray Diffraction (XRD) at different annealing temperatures was also performed on the screenprinted films in order to verify whether the nanostructures remained stable with increasing temperatures. The inset of Figure 3.4 a) shows XRD diffractograms after annealing at 30, 300, 350 and 500 °C. The diffraction peaks match to ZnO with hexagonal symmetry and wurtzite structure (lattice constants a = 3.24982 Å and c = 5.20661 Å) according to ICDD 00-036-1451. There are no significant changes as temperature increases, and the crystallite size determined by the Scherrer method between 100 and 400 °C remains around 73 and 76 nm, respectively, as depicted in Annex F.

From Figure 3.4 b) it is possible to observe not only nanostructures, but also that several particle morphologies are present, namely nanospheroids, nanorods and nanosheets. Clearly, there is not an uniform distribution, neither in shape nor in size of the nanostructures, and numerous aggregates are visible. Still, the way how these different morphologies are organized will provide a good contribution for the semiconducting layer, since a continuous path between them is required for electrical conduction. It was also verified through SEM images that with increasing temperature no visible changes in the nanostructures occur.

The presence of EC is not distinguishable from the SEM images, which is related to the high amount of added ZnO NPs that mask it. Nonetheless, in Annex G an image of the vehicle, which also contains EC, is shown. XRD was also performed on the EC powder and the related diffractogram is depicted in Annex H. In the same annex, the comparison between EC powder and ZnO NPs ink annealed at different temperatures was made. The respective diffractograms revealed that owing to the low amount of the cellulose derivate in the ink it is challenging to obtain a conclusion about the effect of the temperature on the same through the XRD data.

Figure 3.4 c) shows the 3D view of the surface, obtained by AFM, which exhibit an average rms surface roughness of 115.1 nm. This value is associated to the presence of agglomerates, which means that the ZnO NPs are not well dispersed in the vehicle. An alternative suggested to overcome this problem in future developments can be the use of surfactants in order stabilize the nanostructures or
otherwise try to compress the film (e.g. mechanically), since the insertion of stabilizers may impair the performance of the devices as described by Dasgupta *et al.*[5] namely, in terms of mobility. In addition, as reported by the same author, the presence of significant surface roughness between the transistor channel and the electrolyte produces charge traps, which in turn difficult the charge transfer between S/D. The mobility is once again affected. Nevertheless, these drawbacks are intrinsic properties connected to printing techniques.[5]

# 3.2. Characterization and properties of paper ZnO NPs semiconducting layer

## 3.2.1. Structural and morphological analysis of paper coated by ZnO NPs

The top surface of Felix Schoeller raw (FSR) paper, before (see Annex I) and after functionalization (see Figure 3.5 a) was investigated by SEM. The structural unit of the paper is the cellulose fibers, which are formed by several individual cells composed of microfibrils arranged in layers of different thicknesses and angles of orientation. Matching both images, before and after their functionalization, with the XRD diffractograms presented as inset in Figure 3.5 a), it becomes evident that the cellulose fibers were covered by ZnO NPs, with different shapes and sizes (Figure 3.5 b) and **c**)), due to the performed sol-gel method.

The complete reactions for the ZnO nanostructures synthesis can be written as follows:[30]

$$Zn(CH_{3}COO)_{2} \cdot 2H_{2}O + 2NaOH \rightarrow Zn(OH)_{2} + 2CH_{3}COONa + 2H_{2}O \quad (Eq. 3.1)$$
  

$$Zn(OH)_{2} + 2H_{2}O \rightarrow Zn(OH)_{4}^{2-} + 2H^{+} \quad (Eq. 3.2)$$
  

$$Zn(OH)_{4}^{2-} \rightarrow ZnO + H_{2}O + 2OH^{-} \quad (Eq. 3.3)$$

Thus, the presented diffraction peaks at 31.57, 34.21, 36.05, 47.35 and 56.44 ° evidence distinctly the formation of the zinc oxide with hexagonal symmetry and wurtzite structure (lattice constants a = 3.2498 Å and c = 5.2066 Å) according to ICDD card number 00-036-1451. On the other hand at 29.23, 39.29, 43.00 and 48.35 ° calcium carbonate (CaCO<sub>3</sub>) with rhombohedral (lattice constants a = 4.9890 Å and c = 17.0620 Å), is also observable according to ICDD card number 00-005-0586. Its presence is due to the use of pigments that are commonly used in papermaking.[12] As a final point for 14.96°, 16.16°, 22.58°, which correspond to the ( $1\overline{10}$ ), (110), and (002), crystallographic planes of cellulose type I can be associated[75], according to the following ICDD cards number 00-056-1717, 00- 056-1718 and 00-056-1719.



**Figure 3.5** – **a)** The topographical view, obtained by SEM, of the top surface and XRD diffractogram, of FSR paper after being functionalized through the sol-gel method, **b)** and **c)** amplified view of the cellulose fibers and the different obtained nanostructrues of ZnO, respectivelly.

As a result, FSR is suitable for its integration into FETs, since its top surface is reasonably well covered with ZnO, taking once again the role of the semiconductor. Due to the excellent coverage, continuous conductive paths between S and D will be possible, even for higher L. Moreover this coating processes has been done at room temperature and in lab conditions without the requirement of sputtering processes, as reported in the literature.[12]

## 3.2.2. FTIR of the paper coated by ZnO NPs

The ATR-FTIR spectra of the FSR paper, Figure 3.6 b), before and after its surface being functionalized with ZnO nanoparticles is shown in Figure 3.6 a). It is evident, that both spectrums present the same cellulose characteristic peaks namely O-H, C-H and C-O stretching vibrations at 3600- 3000 cm<sup>-1</sup>, 2900 cm<sup>-1</sup> and 1060 cm<sup>-1</sup>, respectively. Another peak at 1640 cm<sup>-1</sup> is also observable and is linked with O-H bending vibration of absorbed water molecules.[12] It is also perceptible, that when the paper is functionalized that a decrease in the intensity of the absorbance peaks is detected. It is known that the most intense peak is the highest amount of material present in the specimen. In this case, it suggests that the number of cellulosic fibers remain the same, but since its surface has been functionalized with ZnO, a lower interaction between the IR beam and the cellulose fibers is possible.[76] This indicates that a layer with a considerable thickness and good coverage of the top surface of the paper was achieved, which has been confirmed previously by structural and morphological analyses.



**Figure 3.6** – **a)** ATR-FTIR spectra of the Felix Schoeller raw (FSR) paper before and after functionalization with ZnO NPs through the sol-gel method and **b)** a piece of FSR paper without and with adhesive kapton tape covering one side.

# 3.3. Characterization and properties of lithium based polymer electrolyte

A combination of succinonitrile (Aldrich), acrylic resin (TB 3003 K, ThreeBond), lithium perchlorate (LiClO<sub>4</sub>, Sigma-Aldrich) and titanium dioxide (TiO<sub>2</sub>) nanoparticles (Rockwood) was used to form a composite solid polymer electrolyte (CSPE), namely a lithium-based polymer electrolyte, in order to be implemented in the EGTs. This type of electrolytes are a good approach for the intended devices fabrication, since it can be printed and thereby will provide fully printed ZnO NPs EGTs, as will be demonstrated later. On the other hand, solid electrolytes are desirable as an alternative to liquid ones for EGTs, as poor mechanical properties, problems with its application (fabrication and devices architecture), safety and resistance to aggressive environments can be minimized or solved.[77] Furthermore, polymer electrolytes have recently been used in applications such as electrochromic displays, thin-film batteries, fuel cells and supercapacitors, showing their versatility.[39]

This lithium-based polymer electrolyte has been developed in CENIMAT|i3N, it has however not yet been fully characterized for the intended application. A rheological characterization has been made in subsection 3.1.1 and it was found, that it behaves as a non-newtonian fluid, (a requirement for screenprinting), achieving a layer thickness of 18.43  $\mu$ m, only with one printing step, and an average rms surface roughness of 261 nm. Figure 3.7 displays the 3D topographic view of the electrolyte surface provided by AFM.



Figure 3.7 – The 3D view of the lithium based polymer electrolyte printed by screen-printing on glass substrate achieved by AFM.

Nevertheless, additional characterization steps are essential, such as electrochemical impedance spectroscopy (EIS) and cyclic voltammetry (CV) in order to understand and determine fundamental parameters that are necessary for further EGT characterization.

# 3.3.1. Electrochemical Impedance Spectroscopy of the electrolyte

The EIS allows to measure the total capacitor impedance (Z) in function of the frequency (f) when an AC voltage is applied to an electrochemical cell at different frequencies. This electrochemical cell is formed by the sample inserted between two identical electrodes as can be seen in Figure 3.8 a). A three-electrode set-up composed by a working electrode (WE), a counter electrode (CE) and a reference electrode (RE) are necessary to perform the measurements appropriately.[78]

An equivalent circuit model (ECM) is also pertinent where it is intended to study the behaviour of the electrochemical cell, as it allows to quantify crucial parameters, such as bulk resistivity ( $\rho$ ), ionic conductivity ( $\sigma_i$ ), bulk capacitance ( $C_b$ ) and EDL capacitance ( $C_{DL}$ ) associated to the used electrolyte.



**Figure 3.8** – **a)** Schematic of the electrochemical cell setup with an area (A) of 1.039 cm<sup>2</sup> and **b)** the corresponding ECM suggested by Dasgupta *et. al* (adapted from [5]).

The selected ECM for electrolyte characterization was previously used by Dasgupta *et al.*[5] An illustration of the model can be seen in Figure 3.8 b), it includes a resistance ( $R_{ext}$ ) that is associated to contact resistances, in this case stainless steel electrodes, in series with an RC circuit and a constant phase element (CPE). Regarding the RC circuit,  $R_b$  embodies the bulk resistance and  $C_b$  the electrolyte bulk capacitance which is associated to the dipolar relaxation of the electrolyte solvent molecules.[5] The CPE symbolises the non-ideal capacitive behaviour due to interface inhomogeneities[79], which corresponds to the line with less than 90° for lower angular frequencies ( $\omega$ ) on the Nyquist plot representation (Figure 3.9 b). An ideal CPE would produce a vertical line for the lowest  $\omega$ , which corresponds to a perfect EDL with no mass transfer in or out of the ZnO NPs ink film.



Figure 3.9 - a) The measured effective capacitance and phases (circles) and the ECM fited curves (lines) and b) the respective nyquist plot of the lithium-based polymer electrolyte.

The data and the fitting provided by the ECM is depicted in Figure 3.9. Firstly, the chosen ECM fits reasonably well the entire frequency spectrum as can be verified for both of the Nyquist Figure 3.9 b) and total impedance graph Annex J. In addition, two domains can be distinguished in Figure 3.9 a) since an electrochemical cell can have a capacitive (for  $\theta < -45^{\circ}$ ) or a resistive ( $\theta > -45^{\circ}$ ) behaviour. Accordantly, for frequencies less than 24 Hz a capacitive domain is verified, which is characterized by a high capacitance from the EDL formation. On the other hand, above this value, ionic relaxation provides a resistive behaviour.[39]

Jovi´c et al.[80] have proposed a model for C<sub>DL</sub> calculation as can be shown in equation 3.4.

$$C_{DL} = \left[Y_0 R_{ext}^{-(\alpha-1)}\right]^{1/\alpha}$$
 (Eq. 3.4)

In equation number 3.4  $Y_0$  is linked to the capacitance of the CPE, and  $\alpha$  is a constant (between 0 and 1) related to the CPE, dictating how non-ideally it behaves. Nevertheless, due to surface roughness and non-uniform current distribution, certain theories refer that  $\alpha$  must be treated as an empirical constant with no real physical basis.[81]

Still, in the present work and as reported by Dasgupta *et al.*[5] and Santos *et al.*[7] the results were determinate merging the selected ECM with the equation 3.4, and  $C_{DL}$  of the electrolyte gives  $2.57 \times 10^{-6} F$ , with an Y<sub>0</sub> of  $2.15 \times 10^{-5} Ss^{\alpha}$ , R<sub>ext</sub> equal to  $117.2 \Omega$ ,  $\alpha$  equal to  $7.38 \times 10^{-1}$  and with the cells area of  $1.039 \ cm^2$ ,  $C_{DL}$  per area corresponds to  $2.47 \times 10^{-6} F \ cm^{-2}$ . Regarding the measured effective capacitance, C<sub>eff</sub>, in Figure 3.9 a), the real value is slightly higher than the value determined which also depends on the C<sub>b</sub> of the electrolyte. However, it is necessary to note that countless factors are involved, such as the cell setup and dimensions, or even the ECM fitting parameters, which also have an associated error (Annex K). Nevertheless, the determined value for C<sub>DL</sub> lies in the standard range for the use of electrolytes in EGTs, i.e. 1-10 µFcm<sup>-2</sup>, as described by Kim *et al.*[8]

The bulk resistance of the electrolyte ( $R_b$ ) was determined, using the ECM fit, as 513.3  $\Omega$ . Consequently the ionic conductivity ( $\sigma_i$ ) of the electrolyte was determined as  $3.09 \times 10^{-7}$  Scm<sup>-1</sup>, using the accepted equation.[7] The ionic conductivity of the lithium-based polymer electrolyte remains in agreement to the reported range for polymer electrolytes which lies between  $10^{-8}$  and  $10^{-4}$  Scm<sup>-1</sup>.[39]

## 3.3.2. Cyclic voltammetry of the electrolyte

The implementation of cyclic voltammetry (CV) dates back to 1964 with the publication of Nicholson and Shain.[82] Thenceforward it became a widely-used electrochemical technique which provides the study of the redox behaviour of compounds, in this case the electrolyte ones, being possible to recognize mechanisms and rates of the oxidation/reduction reactions through a current measured as a function of the linear potential applied. The current-potential polarization curve is due to the faradaic current, which is related to the occurrence of redox reactions, and the capacitive current, which is associated to the double layer charging. Here, as previously mentioned a three-electrode set-up composed by WE, CE and RE is also necessary in order to perform the CV appropriately.[78]

Thus, for the electrolyte characterization using CV, CE and WE of stainless steel were used, as illustrated in Figure 3.8 a) and the electrolyte was deposited, between them, via doctor blade technique.



Figure 3.10 – Cyclic voltammogram of stainless steel/electrolyte/stainless steel capacitor structure at a scan rate of 10 mVs<sup>-1</sup>.

From the cyclic voltammogram of the electrolyte, Figure 3.10, it is noticeable, in the applied potential range (4 to -4 V), that the measured current is mostly capacitive since no redox reactions are visible. This is an expected result, as the stainless steel electrodes do not possess any properties for such reactions. Consequently, the measured current is capacitive, which is due to ionic migration and charge build-up (EDL formation) at the electrode/electrolyte interfaces, as illustrated in Annex L. As the EDLs produce very high electric fields at the interfaces, the measured charging currents become considerable in the order of 0.12  $\mu$ Acm<sup>-2</sup>.[39] High interfacial electric fields are desired, as they are responsible for charge induction into the semiconducting layer of EGTs. Consequently, the electrolyte will be applied as the dielectric layer in the final devices of this work.

# 3.4. Characterization by EIS of the Felix Schoeller raw paper as dielectric layer for FETs

As previously described, the fact that paper can work as an active part in FETs (namely the dielectric), is due to its structure and its composition associated to the papermaking processes. These processes such as the use of pigments and the water mineral content promote the incorporation and accumulation of charges in the cellulose fibers spread in the paper structure.[12] The ionic motion of those ions or charges provides their accumulation at the electrodes/paper interface, exhibiting a behaviour similar to the electrolytes. Therefore, a high capacitance is achieved since an EDL can be formed.[69]

The ECM and electrochemical cell setup, for EIS of the electrolyte, used in the previous subsection (3.3.1), were maintained for the characterization of the FSR paper's dielectric behaviour. However, instead of stainless steel, gold electrodes (area equal to 1.77 cm<sup>2</sup>) were used. Aluminium was evaporated onto the paper in order to improve the electrical contact between electrodes and the disordered cellulose fibres. Figure 3.11 presents the effective capacitance per area and the Nyquist plot, with the respective fitting model.

According to Larsson *et al.*[83], and taking a look on Figure 3.11 a), different polarization mechanisms can be distinguished related to a capacitive (for  $\theta < -45^{\circ}$ ) or a resistive (for  $\theta > -45^{\circ}$ ) behaviour. Including the dipolar relaxation of the material (in this case paper) at high frequencies, ionic relaxation at intermediate frequencies and the electrode polarization at low frequencies, which is responsible for the evident increase of C<sub>eff</sub>. This fact is also related to the electric double-layer (EDL) capacitors formation.[84] These features make FSR suitable as an electrolyte when implemented as dielectric in FETs. The free protons and ions present in the paper structure due to the FSR development and the adsorbed water are linked to the EDL formation near the paper/electrode interface when a voltage is applied.[12][83]



Figure 3.11 - a) The measured effective capacitance and phase (circles) and the ECM fited curves (lines) and b) the respective nyquist plot of the paper.

However it is noticeable, from Figure 3.11 a), that there is not a proper fit between the ECM and the acquired data, neither for Figure 3.11 b) where the Nyquist plot shows discrepancies from the fitting, which evidences that the selected ECM is not suitable for the obtained data. For future works, it is suggested to investigate other possible ECMs in order to acquire a better fitting to these graphs. However, here we can use the obtained fit from the ECM as an approximation to determine the necessary parameters. Using equation 3.4 and the chosen ECM, the CDL of the paper was determined as  $1.79 \times 10^{-12}$  F, with an Y<sub>0</sub> of  $1.10 \times 10^{-6}$  Ss<sup> $\alpha$ </sup>, R<sub>ext</sub> equal to 949.4  $\Omega$ ,  $\alpha$  equal to 0.34 and the cells area of 1.77  $cm^2$ , which corresponds to a C<sub>DL</sub> per area of 1.02  $\times 10^{-12} Fcm^{-2}$ . The respective values used to determine the C<sub>DL</sub> and its associated error can be accessed in Annex M. The determined value for C<sub>DL</sub> is significantly lower than the real effective capacitance measured and depicted in Figure 3.11 a) at 0.01 Hz, which is  $9.03 \times 10^{-7} Fcm^{-2}$ . Annex N shows a magnification of the C<sub>eff</sub> at low frequencies and why the choice of this value. Additionally, if the determined value was considered, it would result in abnormally high field-effect mobility (µFE) for the FETs. In order to have a CDL according to the previously reported works[12] and[13], the measured Ceff will be used for future parameter determination of the FETs. In terms of conductivity, FSR has a value of  $3.37 \times 10^{-8}$  Scm<sup>-1</sup> and in regard to the resistivity a value of  $2.97 \times 10^{-7} \Omega cm$ , considering the accepted equation from the literature [7] and knowing that the resistivity is inversely proportional to the conductivity. For the determined values the measured thickness of the paper is  $1.41 \times 10^{-2}$  cm and a resistance of  $2.37 \times 10^5 \Omega$ , determined from the endpoint of the semicircle in Figure 3.11 b). These values are in agreement with previously reported ones by Pereira et al.[12] when paper was used as the dielectric for FETs based on semiconductor oxides.

## 3.5. Considerations about the selected electrical contacts for ZnO NPs EGTs

For this work, it was only possible to study the staggered-top gate architecture, and as mentioned in section 2.3 ITO, carbon and silver contact layers were used as contact materials. As a starting point, ITO interdigital contacts (resistivity of  $2.32 \times 10^{-4} \,\Omega cm$ ) patterned by lithography were used with the purpose to understand the semiconductor layer performance, when applied in an EGT, as will be possible to see in subsection 3.7.2. Another reason that led us down this path was due to the requirement of temperatures above 300 °C, as discussed previously, to burn-out the vehicle. In addition, as it is well known, both ITO and glass are capable of withstanding such temperatures without having influence on the performance of the devices. Beyond that, carbon and silver inks as electrodes were considered too, as they are going to be used for the fully-printed EGTs. For the initial phase (EGTs with ITO S/D contacts), silver ink from Conductive Compounds was selected as the gate contact. Usually its drying (solvent evaporation) is carried out between 90 seconds to 3 minutes at 130 °C.[85] However, this range of temperature could affect the previously deposited layers, i.e. the lithium-based polymer electrolyte. Therefore, the drying process was conducted at 70 °C during 5 minutes. Furthermore, it was found that the ink resistivity remains equal when dried either under the conditions provided by the

manufacturer or under the ones chosen for our purpose. The drying process should be strictly followed, if poorly made, the ink may be dry at the top but not throughout the film, which can cause adhesion problems, blisters or craters in the ink due to trapped solvents.[85]

Later, for the fully-printed devices, carbon ink was selected for the interdigital S/D electrodes and its drying time 30 minutes at 150 °C provided from ASH was followed[86]. Nonetheless, owing to a lack of information about their properties with temperature, thick films of 5.46 µm were printed on regular glass substrate, from Marienfeld, using a mesh model 120-34. These films were investigated in respect to their behaviour under curing conditions and also under the specific annealing temperatures used for the semiconducting layer. Table 3.1 shows how those temperatures might influence the resistivity of the printed carbon interdigital S/D electrodes.

Drying Process	Resistivity ( $\Omega$ cm)
24 °C	0.743
30 min at 150 °C	0.036
30 min at 150 °C + 30 min at 300 °C	0.024
30 min at 150 °C + 30 min at 350 °C	0.020
30 min at 150 °C + 30 min at 400 °C	0.016
30 min at 150 °C + 30 min at 450 °C	0.018

 
 Table 3.1 – Influence of the curing and annealing temperatures on the resisitivity of the carbon screenprinted S/D electrodes.

The resistivity was determined through the four-point probe technique.[87] It was verified that the resistivity decreases as the temperature increases, improving their electrical conduction in a reasonable temperature range with a slight increase in resistivity at 450 °C. Furthermore, problems associated with adhesion loss or cracks on the same films were not identified.

As a result, it is expected that both ITO, carbon and silver electrodes reveal themselves as appropriate layers for the chosen architecture in order to produce the EGTs, without damage to the interstate layers.

## 3.6. Electrical contacts for paper ZnO NPs FETs

In case of paper ZnO NPs FETs a staggered bottom-gate architecture was chosen since FSR paper is used as substrate, dielectric and semiconductor after being functionalized. Concerning the work that has been developed within CENIMAT|i3N and publications[12] and [13], aluminium was once again chosen for source and drain (S/D) electrodes, deposited via e-beam evaporation, with a thickness of 150 nm. For the gate electrode GZO (200 nm thick) was deposited by RF magnetron sputtering in an AJA ATC 1800 system, without any intentional substrate heating. Figure 3.12 shows an illustration of paper ZnO NPs FET in an interstate structure.



Figure 3.12 - Schematic representation of the developed paper ZnO NPs FETs with an amplification of the functionalized FSR top surface.

## 3.7. Electrical charcaterization of ZnO NPs EGTs

The previous chapters were essential to understand all the fundamental properties of the used layers in the devices under study (ZnO NPs ink as semiconductor layer, lithium-based polymer electrolyte as dielectric and the ITO, carbon and silver electrical contacts). Now, the focus in these next subsections will be on the electrical characterization of the ZnO NPs EGTs, starting by explaining its basic operating principle, followed by the static electrical characterization of the printed EGTs, where the impact of both of the contact materials (ITO and carbon/silver) is investigated. The semiconducting layer of the devices was annealed at the previously determined burn-out temperatures of 300, 350, 400 and 450 °C. This will give insight into the annealing temperature's influence on the performances of the various devices.

#### 3.7.1. The working principle of the built ZnO NPs EGTs

The operation mechanism of the EGTs has been reported to be of two different kinds, depending on the ionic permeability of the semiconductor layer. Therefore, if it is permeable to ions, the devices are classified as electrochemical transistors (ECTs), which is due to the reversible electrochemical doping of the semiconductor supporting the oxidation and/or reduction (faradaic current) of the same. Thus, in ECTs the EDL only occurs at the gate/electrolyte interface. On the other hand, when the semiconductor is impermeable to ions EDL formation at the two interfaces occur (both semiconductor/electrolyte and electrolyte/gate interfaces), creating two parallel layers of positive and negative charges as illustarted in Annex L. The ion movement in the electrolyte results in capacitive currents which can be measured by CV, evidencing the expected charge accumulation Therefore, the electrical double-layer transistor (EDLT) is comparable to a FETs since carrier acumulation or depletion are promoted due to the EDL formation.[6]

Taking into account the EIS and CV characterization of the electrolyte it was expected to obtain devices working as EDLTs but through the CV of electrolyte together with ZnO NPs ink annealted at 350 °C, Figure 3.13 (in a configuration similar to the one presented in Figure 3.8 a)) the presence of faradaic currents were found. These reactions occur between -4 and 4 V for potentials of 2.78 V and - 1.85 V, which could be due to the Li-storage mechanism of ZnO.[88] This mecanism resides in the following two reactions:



(Eq. 3.5) (Eq. 3.6)

Figure 3.13 - Cyclic voltammogram of stainless steel/electrolyte plus ZnO NPs ink/stainless steel capacitor structure at a scan rate of 10 mVs<sup>-1</sup>. The blue data plot represents the cyclic voltammogram for the lithium-based polymer electrolyte and the black one represents the combination of the electrolyte with ZnO NPs ink annealed at 350 °C.

First, the development of Zn metal nanoparticles and Li<sub>2</sub>O is related to the electrochemically discharge of Li metal with ZnO, partially destroying the ZnO crystal structure. Consequently, Zn can additionally react with Li<sup>+</sup> forming the Li-Zn alloy.[89] Nevertheless, these reactions are reversible, and

the associated peaks of 2.78 V and -1.85 V are related to the oxidation process of Zn returning to ZnO, and its consequent reduction, respectively. Although, the literature does not reference any negative applied potencial,[89][88] giving no hint about the reduction voltage observed here. Accordingly, in the applied potential range of the CV, the process deals with a combination of capacitive and faradaic currents. This evidences that ZnO is essentially permeable to ions. Consequently, the fabricated devices should demonstrate a behaviour comparable to an ECT. However, as will be seen later, by analysing the transfer characteristics, it will be demonstrated that the devices work as EDLTs, since no faradaic currents were observed in the I<sub>DS</sub>. Unfortunately, apart from the reported mechanisms, the operation of the EGTs is poorly understood, especially for inorganic semiconductors, making a classification difficult.[7][90]

# 3.7.2. ZnO NPs EGTs

In this subsection the focus will be on the influence of the temperature on the performance of the built ZnO NPs EGTs for both interdigital S/D electrodes. First, no other parameters have been modified apart from the annealing temperature of the semiconductor layer. For these transistors all of the layers, with exception to the ITO interdigital S/D electrodes, have been deposited using the homemade screen-printing technique. So small variations in the thickness and uniformity of the same layers will have influence on the parameters that will be listed. Nevertheless, a sufficient number of samples were determined in order to obtain a reliable statistic on all the average values associated either for the layers thicknesses, or for the width (W) and length (L) of the interdigital ITO electrodes. Some of them were previosly listed, however all of them are summarized again in Table 3.2. It should be noted that the theoretical value for L should be 200  $\mu$ m (mask layout) but was determined as 178.17  $\mu$ m, which is related to variations during mask fabrication, leading to a shorter L. In Annex O, an image of the screen-printed ZnO NPs ink on ITO interdigital S/D electrodes is displayed, as well as the definition of the patterned electrodes and the considered number of the samples for the determination of an average of L and W.

Designation	Average (µm)	Standard deviation (µm)
ITO S/D thickness	0.155	0.0002
ZnO NPs semiconductor thickness at RT	1.39	0.14
Lithium-based polymer electrolyte thickness at RT	18.43	1.23
Silver gate thickness	1.78	0.60
W	68095.72	317.27
1 200	178 17	2 17

 $\label{eq:table_state} \textbf{Table 3.2} - \text{Average and standard deviation of the transistors' layers thickness and W and L of the ITO interdigital S/D electrodes.}$ 

Figure 3.14 shows three transfer curves of ZnO NPs EGTs, in the saturation regime with the same W/L, (382.21) where the semiconductor was annealed at 300, 350 and 450 °C, respectively. As has been reported, the major drawbacks of the EGTs are linked to the large leakage gate current ( $I_{GS}$ ). These can be confimed in the transfer characterisitcs and it influences on the  $I_{DS}$  of the devices, particularly at low and high V<sub>GS</sub>, determining the off current ( $I_{Off}$ ) and limiting the maximum on current ( $I_{On}$ ), respectively. Moreover, the influence of high  $I_{GS}$  may be due to the parasitc capacitance of the electrolye[7] and due to arising charging currents during the EDL formation.

The implementation of another architecture, the scale-down of the EGTs and a careful choice of the applied  $V_{GS}$  in order to exclude the faradaic currents are proposed alternatives to achieve best performances of the devices under study. Also, the replacement by another electrolyte should not be dismissed.



**Figure 3.14** –  $I_{DS}$  –  $V_{GS}$  transfer characteristics, in saturation regime, as well the behaviour of  $I_{GS}$ , for three different annealing temperatures, namely 300, 350 and 450 °C of the ZnO NPs EGTs where ITO was selected for interdigital S/D electrodes.

From the same transfer curves in Figure 3.14, it is noticiable that as the semiconductor annealing temperature increases, both the  $I_{Off}$  and  $I_{On}$  of the devices increases too. This point may be related to an increase in conductivity between the ZnO NPs, which is due to the degradation of EC allowing the development of carbon. Once there, it can promote higher conductivity between the NPs and thus the conductivity of the semiconductor ink increases. Considering the resistive component at low frequencies (capacitive component is negligible) one can derive, from Figure 3.15, that the resistivity (total impedance (|Z|)) decreases with an increase in temperature.



Figure 3.15 - The total impedance |Z| variation with different frequencies of the screen-printed ZnO NPs ink, with different annealing temperatures.

Via SEM analyses it turned out to be quite challeging to conclude if a sinterization of the ZnO NPs was taking place during the temperature increase for the burn-out process since different shapes and sizes are dispersed in the ink. Although, it is known that the sintering temperatures of nanosized structures owing to the high surface-to-volume ratio are considerably lower as compared with the bulk material.[91] Nevertheless, because of the different shapes and sizes, it is difficult to specify what are the necessary temperatures for its sintering. Nonetheless a partial sintering of the nanoparticles should not be excluded, also in relation to the increase of the loff of the devices. Besides that, XRD

measurements indicated an increase of the grain size of the ZnO NPs, as depicte in Annex F which could improve device performances owing to less grain boundaries acting as barrier to electron hopping, as suggested by Bong *et al.*[92]

In addition, all the devices are classified as n-type and normally-off, since at zero V<sub>GS</sub> they are in the off-state. Once in the on-state, all of them can reach an I<sub>DS</sub> in the order of  $10^{-4}$  A, reaching On/Off ratios of 3 orders of magnitude, enhanced by the high double layer capacitante of the lithium-based polymer electrolyte.[93] Relatively to the subthreshold swing (S<sub>s</sub>) which corresponds to the necessary V<sub>GS</sub> to alter the I<sub>DS</sub> by one decade, the devices show a S<sub>s</sub> «1, as can be confirmed in Table 3.3, which provides low power consumption.[94] The low V<sub>On</sub> and the low operation voltages are associated to the use of the litium-based polymer electrolye.[93]

Table 3.3 – Summary of the electric characterization of the ZnO NPs EGTs with ITO as interdigital S/D electrodes, annealed at 300, 350 and 450  $^{\circ}$ C.

Temp (°C)	Vds (V)	<b>V</b> on <b>(V)</b>	On/Off	S <sub>s</sub> (Vdec <sup>-1</sup> )	g <sub>m</sub> (S)	µ <sub>Sat</sub> (cm²(Vs) <sup>-1</sup> )
300	1	0.82	9.84x10 <sup>3</sup>	0.18	2.50 x 10 <sup>-5</sup>	5.29 x 10 <sup>-2</sup>
350	1.2	0.8	4.59x10 <sup>3</sup>	0.22	4.71 x 10 <sup>-5</sup>	9.97 x 10 <sup>-2</sup>
450	0.8	0.45	2.26x10 <sup>3</sup>	0.10	9.68 x 10 <sup>-5</sup>	2.05 x 10 <sup>-1</sup>

Additionally, the saturation mobility ( $\mu_{Sat}$ ) of the devices, since they are working in saturation regime was determined through the equation 3.7[7]

$$\mu_{Sat} = \frac{\left(\frac{d\sqrt{I_D}}{dV_G}\right)^2}{\frac{1}{2}C_i \frac{W}{L}}$$
(Eq. 3.7)

where  $\left(\frac{d\sqrt{I_D}}{dV_G}\right)^2$  is transconductance (gm), W and L corresponds to the width and length of the channel; C<sub>i</sub> is the capacitance of the dielectric layer, which in this case corresponds to the C<sub>DL</sub> (2.47 ×  $10^{-6} Fcm^{-2}$ ). The determined values for µ<sub>Sat</sub> are displayed also in Table 3.3. The applied V<sub>DS</sub> was adjusted for each transistor individually, as only specific values lead to a fully working transistor. It is obvious that different V<sub>DS</sub> lead to variations in each of the transistor's parameters, this was however a necessary measure.

All the quantified values are similar to reported values from the literature namely by Bong *et al.*[32] where ZnO transistors annealed at 280 °C, using an ion gel as electrolyte (drop-casted), were reported with  $12.1 cm^2 (Vs)^{-1}$ ,  $2.64 \times 10^5$ , and 1.16 V as the field-effect mobility, On/Off current ratio, and V<sub>on</sub>, respectively.

In the same way, Santos *et al.*[7] have reported EGTs, where gallium-indium-zinc-oxide (GIZO) nanoparticles were used as semicondutor and a CSPE as electrolyte, all deposited by spin coating. The devices shown On/Off currents ratios between  $10^3 - 10^6$ , S<sub>s</sub> in range of  $0.09 - 0.24 V dec^{-1}$  and  $\mu$  between  $6 \times 10^{-3}$  and  $1 cm^2 (Vs)^{-1}$ .

Likewise, Dasgupta *et al.*[5] have reported ECTs, with ITO nanoparticles as semiconductor and a CPSE, also as electrolyte, both printed by inkjet printing. The devices show  $2 \times 10^4$  on/off currents ratios, a  $\mu_{FE}$  of 5  $cm^2(Vs)^{-1}$ , after subjected to an annealing at 400 °C.

The reported low  $\mu_{Sat}$  for ZnO NPs EGTs can be related to the presence of significant surface roughness between the transistor channel and the electrolyte, provided by the printing technique. Consequently, charge traps are originated, which in turn difficult the charge transfer between S/D as suggested by Dasgupta *et al.*[5] Additionally, contact resistance can also have an influence on the low  $\mu_{Sat}$  as contact between channel and S/D is made by contact points (nanoparticles) instead of a continuous surface.

Closing the electrical characterization subject, Figure 3.16 shows the double-sweep measurements for the three EGTs under study. All of the devices show an anti-clockwise hysteresis performance, which is associated to a slow response of the ions to  $V_{GS}$ . These slow movements at the channel/electrolyte interface maintain the channel open, being necessary to apply at least a voltage

below  $V_{On}$  in order to remove all the ions and thus close the channel. Furthemore, the influence of the listed redox reactions between the ZnO and Li<sup>+</sup> might influence the reported hysteresis since those reactions involve Li<sup>+</sup> intercalation, which hinders the ion migration back into the diffusion layer.



**Figure 3.16** -  $I_{DS}$  -  $V_{GS}$  transfer characteristics for three different annealing temperatures, namely 300, 350 and 450 °C of the ZnO NPs EGTs where ITO as selected for interdigital S/D electrodes The double sweep measurements displays the hysteresis for both transistors as well the influence of  $I_{GS}$ .

However, the depicted I<sub>DS</sub>-V<sub>GS</sub> curves do not show a similar behaviour as reported by Santos *et al.*[7] when ion intercalation into the semiconductor layer takes place. The reached faradaic currents during the CV depicted in subsection 3.7.1 for the electrochemical cell with an area of 1.039 cm<sup>2</sup> amount to 0.17  $\mu$ Acm<sup>-2</sup>. Such faradaic currents could in extreme cases affect I<sub>DS</sub> during the transfer characteristics. These values however, when taking the channel area (0.121 cm<sup>2</sup>) into account, during I<sub>DS</sub>-V<sub>GS</sub> reaches merely 19.57 nA. This value is not high enough to have a significant impact on I<sub>DS</sub> (in the order of 10<sup>-4</sup> A), which is advantageous, as this gives more stable I<sub>DS</sub>. Nevertheless, from the Figure 3.16 fluctuations of I<sub>GS</sub> were observed but they could not be related completely to faradaic currents, as surface roughness, interface quality or contact resistances also have an impact.

In order to achieve fully-printed EGTs (as illustrated in Figure 3.17) the electrical contacts were changed from ITO (photolithography) to carbon/silver ones (screen-printed).



Figure 3.17 – a) Cross-sectional schematic representation of the developed ZnO NPs EGT and b) an image of the fully-printed ZnO NPs EGTs, on glass substrate.

During the development of the fully-printed ZnO NPs EGTs, the biggest bottleneck was related to short circuits between the interdigital and the gate electrodes. As already mentioned, the non-uniform covering of the electrolyte and the applied force on the last screen-printed layer, the silver gate, could be responsible for that. First, due to the high viscosity of the electrolyte, the ink is blocked and it becomes difficult to obtain a uniform printing pattern. Secondly, once the first layer is dry and the next one is

deposited the applied shear rate may result in cracks of the previous layers. As a result, a contact between the two extreme electrodes (S/D and G) is established.

This problem, although not reported previously, happened less frequently with ITO contacts. As ITO has been patterned by photolithography, an uniform and thinner layer is provided, causing a better coverage by the following layers. Looking at the Table 3.4, carbon has a high average thickness compared to the semiconductor and, after being annealed, carbon might be exposed in some areas. Despite the high average thickness of the electrolyte, due to its reported issues associated with deposition, the short circuit often occurs in the fully-printed devices.

In Table 3.4 the average W and L of the fully-printed EGTs is listed. Note that the W was maintained equal, since the same number of samples was considered for all the devices. The only difference lies in L, which theoretically should be 200  $\mu$ m but due to the used printing process, and the mesh form, its value was determined as 243.75  $\mu$ m. In Annex P an image of the screen-printed ZnO NPs ink on carbon interdigital S/D electrodes is displayed, as well as the definition of the pattern electrodes and the considered number of samples for the determination of the average L.

Designation	Average (µm)	Standard deviation (µm)
Carbon S/D thickness	5.46	0.51
ZnO NPs semiconductor thickness at RT	1.39	0.14
Lithium-based polymer electrolyte thickness at RT	18.43	1.23
Silver gate thickness	1.78	0.60
W	68095.72	317.27
L 200	243.75	35.44

 $\label{eq:Table 3.4-Average and standard deviation of the transistors layers thickness and W and L of the carbon interdigital S/D electrodes$ 

Figure 3.18 shows the transfer curves, in the saturation regime, for temperatures of 300 and 400 °C of the fully-printed ZnO NPs EGTs. Therefore, as previously, only the temperature was changed. The observations reported for the previous EGTs are also valid here. Large  $I_{GS}$  continue to influence the performance of the printed devices, hindering  $I_{DS}$ . Once again, redox reaction could occur for the chosen  $V_{GS}$  range (as observed for CV), however as stated beforehand it is challenging to relate  $I_{GS}$  fluctuations (as seen in Figure 3.18) solely to Li<sup>+</sup> intercalation.



**Figure 3.18** –  $I_{DS}$  –  $V_{GS}$  transfer characteristics, in saturation regime, as well as the behaviour of  $I_{GS}$ , for two different annealing temperatures, namely 300 and 400 °C of the ZnO NPs EGTs where carbon was selected for interdigital S/D electrodes.

The annealing temperature of the semiconductor layer also has an influence on an  $I_{Off}$  increase. Still, an evaluation with a device annealed at 450 °C was impossible to show due to the short circuit effects, nevertheless between both temperatures the variation is noticiable. All the devices are also n-type and normally-off reaching on/off ratios with 2 orders of magnitude. The previosuly devices (EGTs with ITO contacts) show an higher On/Off ratio, which is related to lower I<sub>GS</sub> and thus decreased I<sub>Off</sub>. Also, it is noticiable, for the ZnO NPs EGT annealed at 400 °C, that I<sub>GS</sub> impairs its performance, hindering the increase of the I<sub>On</sub>. Regarding the S<sub>s</sub> the devices remain with a S<sub>s</sub> «1, as listed in Table 3.5. In terms of  $\mu_{Sat}$  and g<sub>m</sub> the devices show similar values when compared to those with ITO S/D contacts.

Temp (°C)	V <sub>DS</sub> (V)	Von (V)	On/Off	S <sub>s</sub> (Vdec <sup>-1</sup> )	g <sub>m</sub> (S)	µ <sub>Sat</sub> (cm²(Vs) <sup>-1</sup> )
300	1.1	1.15	9.24x10 <sup>2</sup>	0.21	5.12 x 10 <sup>-5</sup>	1.48 x 10 <sup>-1</sup>
400	0.8	1.13	1.27x10 <sup>2</sup>	0.15	1.40 x 10 <sup>-5</sup>	4.06 x 10 <sup>-2</sup>

Table 3.5 - Summary of the electrical characterization of the ZnO NPs EGTs with carbon as interdigital S/D electrodes, annealed at 300, and 400  $^\circ$ C.

The output characteristics for both fully-printed ZnO NPs EGTs, annealed at 300 and 400 °C, respectively, are displayed in Figure 3.19. Both do not reveal a hard saturation domain, which can be related to electrical contact effects.[13] In addiction, for V<sub>GS</sub> up to 2 V, this saturation regime is impaired, possibly owing to the competition between I<sub>DS</sub> and I<sub>GS</sub>. Furthermore, should be noted as already mentioned, that the V<sub>DS</sub> and V<sub>GS</sub>, was adjusted for each transistor individually, as only specific values lead to a fully working transistor.



Figure 3.19 - The drain current –drain voltage ( $I_{DS}$ - $V_{DS}$ ) output characteristics for both full-printed ZnO NPs EGTs.

Regarding the double sweep measurements, as depicted in Figure 3.20, the devices show, as expected, an anti-clockwise hysteresis, which are, once again, related to a slow ion migration. When sweeping back, the EDL is kept intact until reaching  $V_{On}$ . This process keeps the channel open until that voltage is reached. When  $V_{GS}$  falls below  $V_{On}$  the EDL collapses and  $I_{DS}$  starts to drop. The transistor however does not reach the complete off-state, which can be related to trapped charges at the electrolyte/semiconductor interface.[5]

The results obtained, for both types of devices, show that there are still some negative aspects which need to be taken into consideration in order to maximize the performance of the fabricated devices with the aim of minimizing the reported problems. On the other hand, the achieved results with the use of printing techniques, particularly in the field of inorganic EGTs are definitely worth to highlight. The annealing temperatures, which are fundamental in order to burn the vehicle out and thus achieve good electrical modulation are not yet low enough for the documented ZnO NPs EGTs to be built on flexible substrates such as paper or PET.



**Figure 3.20** –  $I_{DS}$  –  $V_{GS}$  transfer characteristics, in saturation regime for two different annealing temperatures, namely 300 and 400 °C of the ZnO NPs EGTs where carbon was selected for interdigital S/D electrodes. The double sweep measurements displays the hysteresis for both transistors as well as the influence of  $I_{GS}$ .

#### 3.8. ZnO NPs ink as UV photodetector

As a last point, related to the ZnO NPs thick films, this section will provide the behaviour of fully screen-printed films as UV light photodetectors, another valuable application of the fabricated devices.

The time response of the prepared ZnO NPs ink was characterized using a Gamry Instruments Reference 600 Potentiostat, in a chronoamperiometry configuration with the application of a continuous 1 V dc between S and D. For the sample preparation, the steps number 2 and 3 described in Annex A were used. Figure 3.21 depicts an image of the screen-printed ZnO NPs photodetector and its time response after being annealed at 300 °C and subjected to UV radiation with an ultraviolet lamp, model TK-2028 (intensity of 6 W at a wavelength of 254 nm). The sensibility of the photodetector was tested under dark (UV OFF) and light (UV ON) as designated in the figure.



**Figure 3.21** – The time response of the screen-printed ZnO NPs photodetector, after annealing at 300 °C, under OFF and ON UV light radiation. An image of the photodetector is displayed in the inset, where the black pattern corresponds to the screen-printed carbon interdigital S/D electrodes and the top coating (white) corresponds to the screen-printed ZnO NPs ink.

The photoresponse of the ZnO is associated to the surface-adsorbed species, namely oxygen molecules, and the volume process.[95] Under ambient conditions, without UV exposure, the oxygen molecules are capable to adsorb at the ZnO NPs surfaces capturing its free electrons. Additionally, a depletion zone is formed with lower conductivity and negatively oxygen ions on the surface of the nanoparticles. Once exposed to the UV light, electron-hole pairs are produced with energies higher than the ZnO NPs bandgap. Thus, the generated holes are responsible for a reduction of the previously

depleted zone, discharging the induced negatively oxygen ions. Meanwhile, those oxygen molecules are photodesorbed from the ZnO NPs surface and free electrons are photogenerated. Accordingly, an increase in the conductivity of the ZnO NPs is manifested owing to the depletion zone reduction and the electrical resistance reduction. Turning off the UV light, a decrease in the conductivity occurs owing to the adsorption of oxygen molecules.[95][96]

In Annex Q the exponential fitting and the extracted parameters associated to the rise time  $(\tau_r)$  and the fall time  $(\tau_f)$  for the three cycles are shown. The determined times show that the  $\tau_r$  are larger than the  $\tau_f$ , which means that the rate desorption of oxygen molecules on the ZnO NPs surfaces is slow relatively to the adsorption. Nevertheless, from Figure 3.21, it is possible to verify the velocity, stability and repeatibility of the screen-printed UV photodetector during the investigated cycles.

## 3.9. Electrical characterization of paper ZnO NPs FETs

This section aims to show results on the static electrical characterization and investigate the performance of the fabricated paper ZnO NPs FETs. Figure 3.22 presents the transfer characteristics ( $I_{DS}$ - $V_{GS}$ ) as well the  $I_{GS}$  in saturation regime of the two selected paper ZnO NPs FETs, namely X1Y2 and X2Y3, respectively. As illustrated in the inset of Figure 3.22, the only difference between both transistors relies in the W/L.



Figure  $3.22 - I_{DS} - V_{GS}$  transfer characteristics, in saturation regime, as well as the behaviour of I<sub>GS</sub> in paper ZnO NPs FETs using to different W/L: 6.6 and 10.6, respectively.

Thus, the transfer characteristics, as well as Table 3.6 depict the influence of the W/L variation on the performance of the devices. As expected, they exhibit n-channel behaviour since ZnO NPs were used with the purpose to functionalize the randomly distributed cellulose fibers. In addition, they behave as normally-off devices since at zero V<sub>GS</sub> they are in the off-state. The listed low V<sub>On</sub> are associated to the  $g_m$  values.[15]

 Table 3.6 - Summary of the electrical characterization of the paper ZnO NPs FETs with W/L of 6.6 and 10.6, respectively.

Transistor	V <sub>DS</sub> (V)	<b>V</b> on <b>(V)</b>	On/Off	S <sub>s</sub> (Vdec <sup>-1</sup> )	g <sub>m</sub> (S)	µsat (cm <sup>2</sup> V <sup>-1</sup> s <sup>-1</sup> )
X1Y2	15	0	2.16x10 <sup>2</sup>	1.79	1.44 x 10 <sup>-8</sup>	4.83 x 10 <sup>-3</sup>
X2Y3	15	1.5	6x10 <sup>1</sup>	2.95	2.35 x 10 <sup>-9</sup>	4.90 x 10 <sup>-4</sup>

Furthermore, the difference between the achieved On/Off ratio for both transistors can be related to the poor interface quality between the dielectric, FSR paper, and the ZnO NPs, since cellulose fibers are randomly distributed between the S/D electrodes and its functionalization is hardly uniform. In

addition, the low S<sub>s</sub> and low  $\mu_{Sat}$  can be related to poor electrical contacts between single cellulose fibers and thus compromises ZnO NPs matrix interconnectivity. Consequently, device parameters do not scale linear with L (as is the case for thin-film transistors) since we are dealing with a NPs matrix and not a continuous film.

The double-sweep measurements for both paper FETs, in saturation regime are depicted in Figure 3.23. It is noticeable that a large anti-clockwise hysteresis is established and ion migration and charge trapping effects are the sources as suggested by Martins *et al.*[70] Paper structure and its constitution provides the charge retention.



**Figure 3.23** –  $I_{DS}$  –  $V_{GS}$  transfer characteristics, of the paper ZnO NPs FETs, in saturation regime using to different W/L: 6.6 and 10.6, respectively. The double sweep measurements displays the large hysteresis for both transistors as well as the influence of  $I_{GS}$ .

Accordingly, following the observed hysteresis, when V<sub>GS</sub> is increasing, the ions are forced to move near the ZnO NPs and cellulose fibers interface, in other words to the channel interface, establishing a charged layer, composed of charges with opposite signs, identical as already mentioned for EGTs. When channel modulation is established, due to the electric field sustained between gate electrode and the semiconductor, the FET is in the on-state and the enhancement of I<sub>DS</sub> is related to the electron accumulation, in the channel transistor due to the increase of V<sub>GS</sub>. When V<sub>GS</sub> starts to decrease, the transistor remains in the on-state, being necessary to apply V<sub>GS</sub> lower than - 20 V in order to achieve the initial I<sub>Off</sub>, for both devices, and consequently reach the off-state. The described mechanism is linked to a write-erase information process, since the charges during the on-state are trapped in the FSR paper structure.[97] The charge trapping of protons (H<sup>+</sup>) as well as hydroxyls (OH<sup>-</sup>) are an example of these charges owing to the dissociation of the water adsorption onto the cellulose fibers' surface. For instance, in the case of H<sup>+</sup> it can link to the ZnO NPs surface and can therefore be trapped between them and the cellulose fibers.[12] This behaviour could be advantageous for selected applications in paper logic gates, where the off- and on-states represent the logic values 0 and 1, respectively.

In order to reduce the large hysteresis, as well as the  $I_{GS}$ , a decrease in paper roughness, a minimization of the charge carrier traps or the use of low ion bombardment deposition processes, are described as possible solutions in the literature.[97] Also, the compactness of the paper, the scaling down of the built devices, as well as the gate electrode area reduction are key factors suggested to decrease  $I_{GS}$ [15] and should be considered in future work. An implementation of interdigital S/D electrodes should also be considered, as it would allow more conductive paths on the randomly functionalized cellulose fibers.

The printing techniques, such as screen-printing could be a good alternative to the used PVD technique in order to deposit the electrical contacts in paper ZnO NPs FETs, meanwhile it can replace the ion bombardment deposition processes, making the manufacturing process more cost-effective.

# 4. CONCLUSIONS AND FUTURE PERSPECTIVES

In the present work, the main objectives were successfully achieved as follows:

- ZnO NPs EGTs were developed taking advantage of printing techniques, namely screenprinting. Through that, fully-printed ZnO NPs EGTs were fabricated by using different inks, with special attention on the dispersion of ZnO NPs in ethyl cellulose. This ink acted as the semiconducting layer and a CSPE as the dielectric.
- 2) Paper ZnO NPs FETs were developed using a sol-gel method, based on ZnC<sub>4</sub>H<sub>6</sub>O<sub>4</sub>·2H<sub>2</sub>O and NaOH. Thus, the paper top surface was functionalized in order to build a semiconducting layer. Therefore, in an interstate transistor structure, paper could play three different roles: substrate, dielectric and semiconductor after its functionalization.

The electrical characterization of the final devices, EGTs and FETs, was performed in order to understand their performances. The next sections are focused to provide some final inferences about the work carried out, as well as some future perspectives.

## 4.1. Final conclusions

Screen-printing has proven to be a useful printing technique with the purpose to build fullyprinted EGTs. Although, short circuit is an issue, especially on the fully-printed devices as stated beforehand, owing to the non-uniformity of the screen-printed electrolyte layer. Since the main advantage of the EGTs lies in the implementation of high capacitance CSPEs as the dielectric layer, during EIS the lithium-based polymer electrolyte displayed a  $C_{DL}$  of 2.47 × 10<sup>-6</sup> Fcm<sup>-2</sup>, which allowed low operation voltages, between - 2 and 4 V.

The required temperatures used to burn-out the vehicle, of the semiconducting layer, and achieve good electrical modulation, were seen to be at least of 300 °C, making it impossible to be implemented on flexible substrates, such as PET or paper. Additionally, the applied temperatures promote a decrease in adhesion of the semiconductor layer to the glass substrate, as soon as EC was fully degraded. On the other hand, EC showed to be an indispensable part of the developed ZnO NPs ink, providing the intended rheological properties, as well as the deposition of the ZnO NPs onto the substrate. The working temperatures support an increase in loff and lon of the printed devices. This fact suggests an increase in conductivity of the ZnO NPs films with temperature. The used characterization techniques (FTIR, SEM, DRX, EIS) were fundamental for understanding the involved phenomena. Therefore, some crucial conclusions were taken, including the possible presence of carbon between the nanoparticles due to EC degradation, a small increase of the grain size or a partial sintering of the NPs.

Regarding the final devices, for the applied V<sub>GS</sub>, the ZnO NPs EGTs are affected by capacitive currents. These are a consequence of the EDL formation (responsible for channel induction) by ion accumulation at the semiconductor/electrolyte interface in EGTs. On the other hand, during CV measurements, where the electrochemical cell was constituted of ZnO and the lithium-based polymer electrolyte, faradaic currents were also found. These faradaic currents are a consequence of reduction and oxidation reactions of the ZnO NPs, owing to its Li<sup>+</sup>-storage mechanism. However, an impact on the lbs of the devices was not perceived, which could be connected to the reduced channel area (0.121 cm<sup>2</sup>) when compared to the electrochemical cell area (1.039 cm<sup>2</sup>).

Low mobilities  $(1.48 \times 10^{-1} \text{ cm}^2 (Vs)^{-1})$  were a result of the induced charge traps supported by large surface roughness between both of the printed layers, namely the semiconductor and the electrolyte, owing to the presence of agglomerates. Furthermore, the contact between channel and S/D is provided by contact points instead of a continuous surface, so a contact resistance could be responsible for the low mobilities. Nevertheless, the devices showed On/Off ratios of around  $10^3$ , S<sub>s</sub> < 1 Vdec<sup>-1</sup> and g<sub>m</sub> around  $10^{-5}$  S. However, high I<sub>GS</sub> were found which hindered the performance of the final devices. High parasitic capacitances of the electrolyte and the charging currents during the EDL formation are the suggested sources. In addition, all the devices showed an anti-clockwise hysteresis

behaviour, owing to a slow response of the ions to the applied  $V_{GS}$ . For the same range, the redox reactions between ZnO and Li<sup>+</sup> might contribute to a slower response with electron release.

In case of paper ZnO NPs FETs, the used sol-gel method worked reasonable well in order to functionalize the randomly distributed cellulose fibers, at room temperature, with ZnO NPs as evidenced by SEM and XRD. It was found that the selected ECM during EIS was not suitable for the determination of the paper's C<sub>DL</sub>. Therefore the C<sub>eff</sub> at the lowest frequency of 0.01 Hz was considered as the real C<sub>DL</sub>, where FSR exhibited a C<sub>DL</sub> of  $9.03 \times 10^{-7} Fcm^{-2}$ . This value suggests that FSR at low frequencies behaves as an electrolyte, allowing its application as the dielectric layer in FETs. This C<sub>DL</sub> determination however does not take any contact resistances or even the CPE into account, as previously used for the CSPE.

The transfer characteristics of the paper ZnO NPs FETs, in the saturation regime, showed a normally-off performance. In addition, they can work in a wide range of potentials, ranging from - 30 to 30 V, with V<sub>On</sub> less than or equal to 1.5 V for a V<sub>Ds</sub> equal to 15 V. Moreover On/Off ratios of two order of magnitude were achieved, as well as  $S_s = 1.79 V dec^{-1}$ ,  $g_m$  in the order of  $10^{-8}$  S and  $\mu_{Sat}$  of  $4.83 \times 10^{-3} cm^2 (Vs)^{-1}$ . Poor electrical contact between the ZnO NPs and the cellulose fibers could be responsible for the low mobilities, resulting from a non-uniform field effect. Finally, the double-sweep measurements described a large anti-clockwise hysteresis, which was related to the ion migration and charge trapping over the paper structure. This process can open routes to fully-printed memory devices, owing to the write erase properties.

# 4.2. Future perspectives

Regarding the inorganic EGTs, only a few publications are available and its reported working principle is poorly understood. The present work is a novelty, since by using only screen-printing technique it was possible to develop a fully printed ZnO NPs EGTs. Nevertheless, with the aim of improving the performance of the devices, their reliability and better understand its mode of operation, several aspects come to mind and should be considered for future works.

Essentially, inks are the core of the performance of these devices, so a detailed attention needs to be given to the ink formulation, as well as its stability without adversely affecting the surrounding layers. Moreover, thermal sintering is a fundamental step, in order to burn-out the binders and surfactants, and once again, they must be well chosen to prevent deterioration of the layers or even the substrate. For the present work, photonic sintering could be a good choice with the aim to fully degraded EC, as has already been confirmed in ongoing works. Therefore, the use of such high temperatures might not be necessary, which will enable the development of these devices on flexible substrates. However, precautions must be taken, owing to the photosensitivity of the ZnO without affecting its performance in the EGTs. Besides that, the increase of the ZnO NPs concentration and its dispersion, in the ink, would also be valuable as has been confirmed in ongoing works, where electrical modulation of the fully-printed EGTs was achieved at processing temperatures lower than 150 °C.

Other important factors like surface energies, as well as the wettability either of the inks or the substrates are significant in order to acquire lines of high-resolution and should receive greater attention in future works.

Recently, organic dispersants, manufactured by Fujifilm Sericol Ltd, such as Plastijet XG 383 and Plastijet ZV558, were reported in order to disperse ZnO Nanorods (NRs). For this approach, only temperatures of up to 90 °C, as the sintering temperature, would be necessary.[28] Additionally, the incorporation of ZnO NRs in the semiconductor ink, for the proposed EGTs, could be beneficial, promoting better electrical conduction between S/D electrodes owing to less boundary effects between individual NRs. In addition, the devices could be built on flexible substrates and other device architectures could be considered.

The use of an automatic screen-printing station would also be beneficial, since snap-off, shear rate, angle, geometry and squeegee type could be investigated. Consequently, a better understanding of its influence on the performance of the devices will be possible.

Regarding the electrolyte layer, others CSPE should be studied and implemented, in order to achieve an  $I_{GS}$  with less impact on the performance of the devices. Additionally, with aim to evaluate

their performances over the time, encapsulation procedures should be considered because ambient conditions have an impact, for instance on the electrolyte's lifetime, or even on the silver gate (oxidation issues).

As a last point, regarding the paper electronics subject and as demonstrated in this work, paper could play three different roles: substrate, dielectric and semiconductor after its functionalization in an interstate transistor structure. Therefore, it would be useful to apply, once again, printing techniques like screen-printing with aim to pattern the electrical contacts, including an interdigital structure (as it would allow more conductive paths on the randomly functionalized cellulose fibers). This would exclude the use of PVD techniques. As well, as paper is being used, it will also be important to verify the influence of the ambient conditions, namely the water content, since it is crucial for its dielectric properties and thus the overall performance of the intended devices.

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# 6. ANNEX

# Annex A

Fully description of all steps that were taken for the fabrication of both, the interdigital S/D electrodes, as well as for the fully-printed transistors and lastly for the paper ZnO NPs FETs.

- For ITO source/drain (S/D) electrodes, the desired interdigital pattern was obtained via 1. photolithography on an ITO pre-coated glass (Xin Yan Technology,  $155 \pm 20$  nm of ITO,  $15 \Omega/_{\Box}$ ,  $T \ge 85\%$  at 550 nm. Firstly, the photoresist AZ1518 was spin coated on the ITO pre-coated glass using a Karl Suss SM 240 spin coater, at 1000 rpm for 10 seconds, for film uniformization, and afterwards at 3500 rpm during 20 seconds, for excessive photoresist removal and thickness definition. Then, a softbake was performed at 120 °C on a hotplate, with the purpose to decrease the solvent content in the photoresist and in turn increase its adhesion to the substrate. After this, a Karl Suss MA 45 mask aligner was used to expose the photoresist, to UV light during 30 seconds. For that, first the substrate was aligned under proximity mode and subsequently, exposed in contact mode. The resist development was carried out using a metal-ion-free AZ 726MIF Developer followed by cleaning with ultra-pure water and drying with nitrogen. The ITO was etched with a FeCl<sub>3</sub>:HCl (1:1) solution at 70 °C for 1 min and 15 seconds. Afterwards the substrate was cleaned and dried with ultra-pure water and nitrogen. As a final step, the glass substrate, containing the desired pattern and the photoresist was immersed, first in acetone, secondly in isopropanol (IPA) and thirdly in ultra-pure water in order to remove the AZ1518 and finally dried using nitrogen.
- 2. For carbon source/drain electrodes, the interdigital pattern was defined using a mesh model 120-34 (mesh count 305, aperture 45 μm and thread diameter 34 μm) on a regular glass substrate from Marienfeld (previously, subjected to an UV-irradiation during 15 min through a UV-Ozone Cleaner Novascan PSD –UV ), followed by curing at 150°C, for 30 minutes. The carbon paste (TU-10s) was obtained from Asahi Chemical Research Laboratory Co., Lda.

Then, the following steps were trailed for both types of source/drain electrodes:

- The semiconductor was printed with a mesh model 77-55 (mesh count 190, aperture 81 μm and thread diameter 55 μm), followed by 30 min annealing on a hotplate at different temperatures for each semiconductor sample, ranging from 300 °C to 450 °C, with a step of 50 °C.
- 4. Followed by the deposition of the lithium-based polymer electrolyte, composed of succinonitrile (Aldrich), acrylic resin (TB 3003 K, ThreeBond) lithium perchlorate (LiClO<sub>4</sub>, Sigma-Aldrich) and titanium dioxide nanoparticles (TiO<sub>2</sub>, RockWood). The same mesh model was used, followed by a 5 minutes UV-exposure, and a 5 minutes cure at 70 °C on a hotplate.
- 5. Finally, the silver gate electrode was printed using the same mesh model used to print source and drain electrodes, followed by a 5 minutes cure at 70 °C, also on a hotplate. The silver ink (PE-AG-530 Flexible Silver Conductive Ink) was obtained from Conductive Compounds, Innovative Chemistry for High-Tech Applications.

Considerations: the screen-printing station used for film deposition is a homemade system (Figure 1.3), all the meshes used to define the desired pattern were polyester screens and a rubber squeegee was used to print. Moreover, before coating, all the glass substrates were immersed in acetone and IPA in an ultrasonic bath each for 5 min, subsequently washed with de-ionized water, and then dried using nitrogen.

## Paper ZnO NPs FETs

As mentioned in 2.2, the first step consisted in growing ZnO nanoparticles on the cellulose fibers on the surface of FSR paper. Afterwards, source and drain (S/D) electrodes were deposited via e-beam evaporation, through a shadow mask, with the following dimensions: channel widths (W) of 2220  $\mu$ m and 1390  $\mu$ m, but both with the same channel length (L) of 210  $\mu$ m, achieving a W/L of 10.6 and 6.6, respectively. For the S/D electrodes, aluminium (AI) contacts with thicknesses of 150 nm were used. In

order to achieve the desired staggered bottom-gate architecture, 200 nm thick of gallium zinc oxide (GZO) gate electrodes were deposited, on the opposite side of the paper, by RF-magnetron sputtering in an AJA ATC 1800 system, at room temperature

# Annex B



Figure 6.1 – An example of the non-uniformity screen-printed electrolyte film, on glass substrate.

# Annex C



Figure 6.2 - TG-DSC curves of pure EC from Aldrich

# Annex D

For Ethanol O-H stretch, hydrogen bonded at  $3500-3200 \text{ cm}^{-1}$ , C-H stretch at 2971-2870 cm<sup>-1</sup> and C-O stretch between 1100 and 1040 cm<sup>-1</sup>. In case of Toluene, the interval between 3100 and 3920 cm<sup>-1</sup> is linked to the C-H stretch as well between 1080-670 cm<sup>-1</sup> and finally the C-C stretch between 1600 and 1400 cm<sup>-1</sup> which corresponds to the stretches in the aromatic ring.[98]



**Figure 6.3** – ATR-FTIR spectrum of the compounds, in solution form except in the case of EC (powder), used in the preparation of ZnO NPs ink.



Figure 6.4 - ATR-FTIR spectra of the ZnO NPs ink after being screen-printed and annealeted at different temperatures from 24 to 450 °C.

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# Annex F

Scherrer equation

$$D_{hkl} = \frac{0.9\lambda}{\beta cos\theta}$$

 $D_{hkl}$  is the crystallite size in the direction normal to the hkl lattice planes,  $\lambda$  is the x-ray radiation wavelength,  $\beta$  is the full width at half-maximum (FWHM) of the diffraction peak and  $\theta$  is the corresponding Bragg angle.

The diffractograms obtained were analysed with a specific software (HighScore Plus) that allows the deconvolution of K $\alpha_1$  and K $\alpha_2$  cases. The data obtained from the XRD measurements are treated to obtain more accurate information on peak parameters such as position, intensity, width and shape. Using the software, the background was determined, the peaks were identified (K $\alpha_1$  and K $\alpha_2$  not separated) and it was possible to fill the profile of the peaks, in which K $\alpha_1$  and K $\alpha_2$  are deconvoluted. The peak profile characteristics were calculated by applying adjustable, mathematical profile functions. The software also calculates the FWHM.[13]



Figure 6.5 – The variation in cristallite size of the ZnO NPs with temperature.

## Annex G



Figure 6.6 - The topographical view, obtained by SEM, of the screen-printed vehicle on glass substrate.

### Annex H



Figure 6.7 – The XRD diffractogram of the EC powder and the ZnO NPs ink screen-printed on silicon substrate and annealed at the inset listed temperatures.

## Annex I



Figure 6.8 – The topographical view, obtained by SEM, of the top surface of FSR paper before being functionalized with ZnO NPs.

## Annex J



Figure 6.9 – Total impedance |Z| variation with different frequencies.

# Annex K

Table 6.1 – Extracted parameters for the selected ECM with associated error to the determination of  $C_{DL}$  of the lithium-based polymer electrolyte.

ECM	Value	Error
R <sub>ext</sub> (Ω)	117.2	8.542
Y <sub>0</sub> (Ss <sup>α</sup> )	2.15 x 10 <sup>-5</sup>	1.91x10 <sup>-7</sup>
α	0.738	0.00251
R <sub>b</sub> (Ω)	513.3	8.317
C <sub>b</sub> (F)	6.08 x 10 <sup>-10</sup>	2.36 x 10 <sup>-11</sup>

# Annex L



**Figure 6.10** – Schematic representation of the charge mechanism in an electrolytic parallel plate capacitor and the voltage profile plus the electric field distribution **a**) where no voltage is applied, **b**) instantly after the voltage being applied, the dipolar relaxation, **c**) the ionic relaxation of the ions leading to the EDL starting to build up, and **d**) the EDL formation at the electrode/electrolyte/electrode interfaces. Adapted from [39].

## Annex M

ECM	Value	Error
R <sub>ext</sub> (Ω)	949.4	45.08
Y <sub>0</sub> (Ss <sup>α</sup> )	1.10 x 10 <sup>-6</sup>	7.671x10 <sup>-9</sup>
α	0.34	0.00274
R <sub>b</sub> (Ω)	1.48 x 10 <sup>5</sup>	1.85 x 10 <sup>3</sup>
$C_{b}$ (F)	8.94 x 10 <sup>-11</sup>	6.46 x 10 <sup>-13</sup>

**Table 6.2** – Extracted parameters for the selected ECM with associated error to the determination of  $C_{DL}$  of the Felix Schoeller raw paper.

# Annex N



Figure 6.11 – Magnification of the measured effective capacitance and phase (circles) and the ECM fited curves (lines) for FSR paper

#### Annex O



Figure 6.12 – a) Screen-printed ZnO NPs ink deposited on ITO interdigital S/D electrodes. The white lines beneath the ZnO NPs film correspond to the patterned electrodes and b) shows an amplification of the patterned electrodes. The table in c) shows the selected number of samples for the determination of the channel length (L) for the L 200 ITO S/D interdigital electrodes.

Number of samples for W (µm)					
5082.70	5695.18	5987.67	5691.18		
4966.21	5643.12	5627.03	5846.96		
5034.45	5918.02	5595	6124.07		
5627.10	5907.43	5677.37	6031.77		
5687.14	5623.04	5647.29	6080.02		
	Average				
5674.64					
Standard Deviation					
317.27					

Table 6.3 – The selected number of samples for channel width (W) determination.

Note that W was determined at 68095.72  $\mu$ m which result from multiplying the average value by 12, which is the total number of fingers of the patterned interdigital structure (ITO or carbon), where channel formation can take place.

## Annex P



**Figure 6.13** - **a)** Screen-printed ZnO NPs ink deposited on carbon interdigital S/D electrodes. The light grey lines correspond to the pattern electrodes and **b)** shows an amplification of the patterned carbon electrodes. The table in **c)** depicts the selected number of samples for the determination of the channel length for the L 200 carbon S/D interdigital electrodes.

## Annex Q

**Table 6.4** – The determined rise and fall time ( $\tau_r$  and  $\tau_f$ , respectively) by exponential fitting on the time response of the screen-printed ZnO NPs ink (after annealing at 300 °C) as an UV-photodetector under OFF and ON UV light radiation for 3 cycles.

Designation	Time (s)	Standard error
$ au_{r1}$	33.99	0.21
$ au_{f1}$	13.30	0.05
$ au_{r2}$	20.70	0.09
$ au_{f2}$	14.64	0.06
$ au_{r3}$	24.74	0.14
$ au_{f3}$	15.07	0.06


**Figure 6.14** – The time response of the screen-printed ZnO NPs ink, after annealing at 300 °C, as UV photodetector under OFF and ON UV light radiation. The blue lines correspond to the rise time ( $\tau_r$ ) exponential fitting while the black ones are linked to the fall time ( $\tau_f$ ) exponential fitting for 3 cycles.